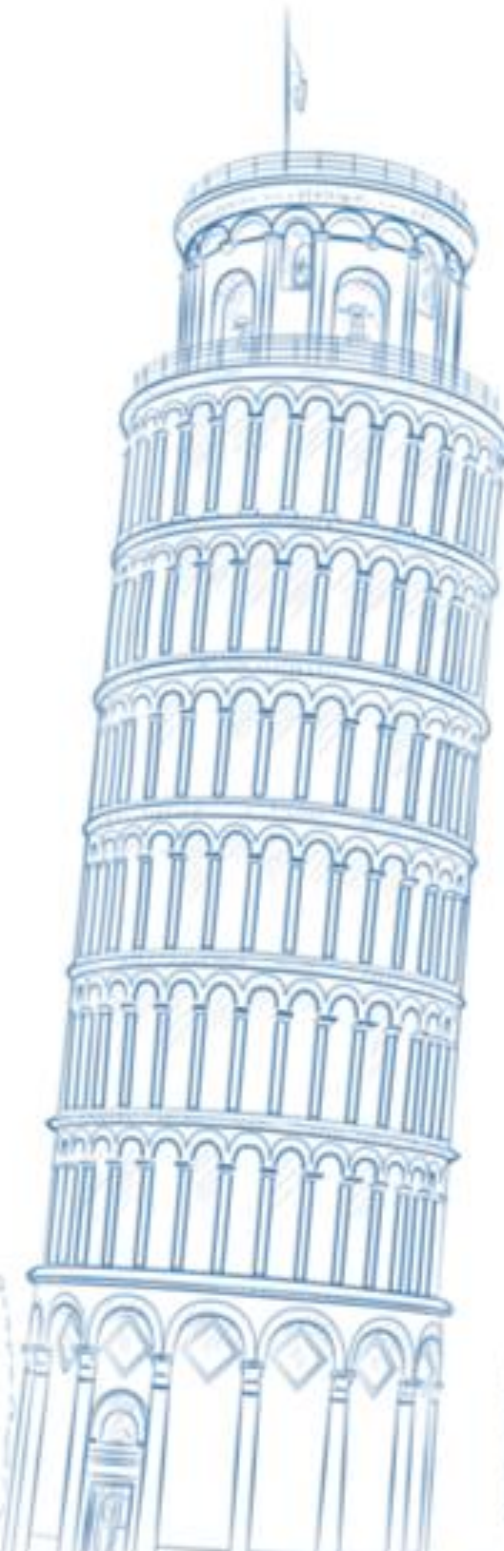


# Quantum transport in dual-channel **InAs/InP/GaAsSb** core-shell nanoscale devices and Graphene/ultrathin- $\text{Si}_3\text{N}_4$ heterostructure device

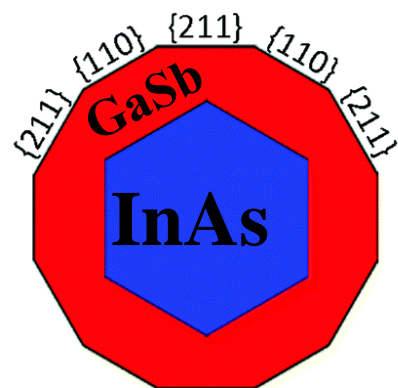
Sedighe Salimian

National Enterprise for nanoScience and nanoTechnology

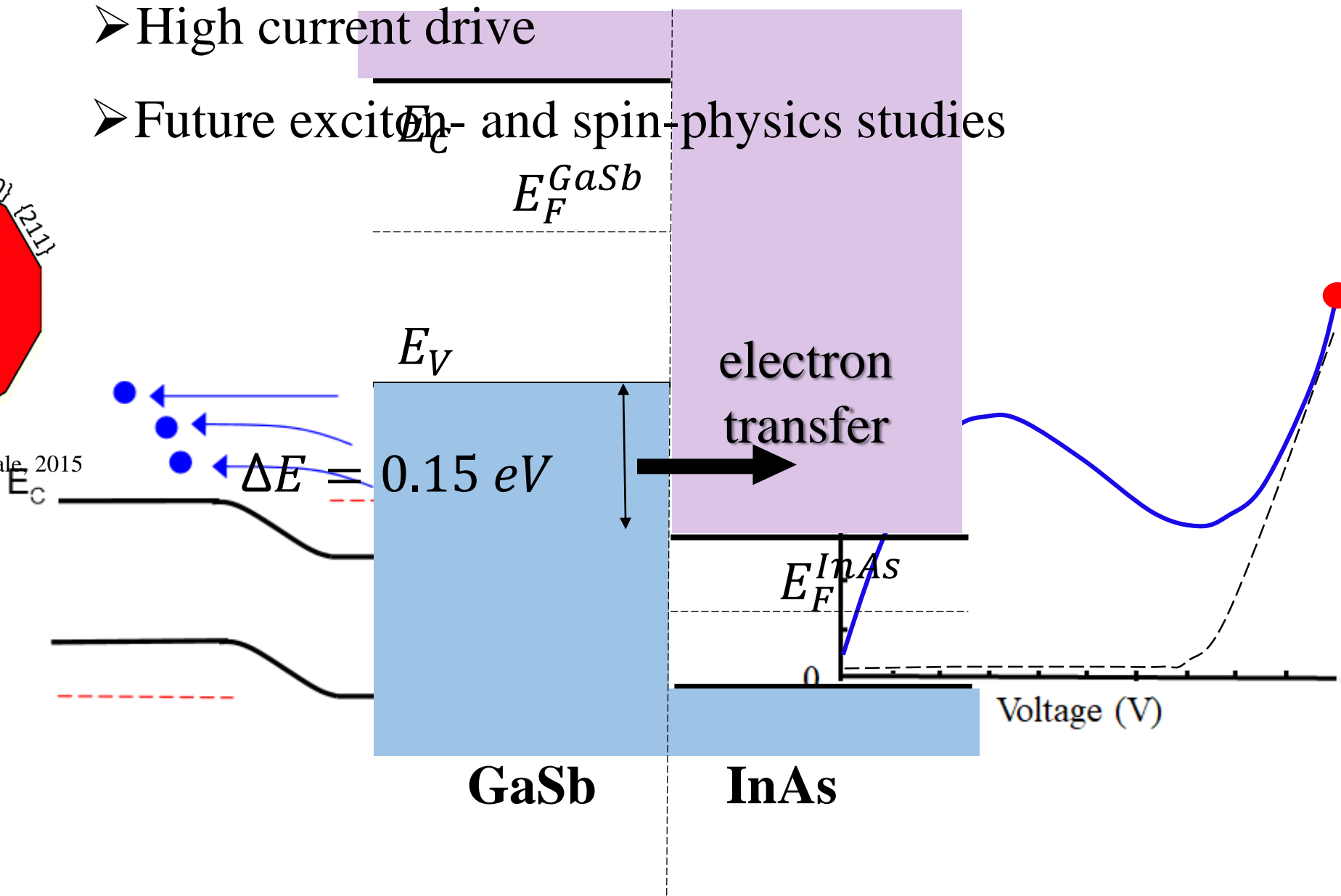
NEST

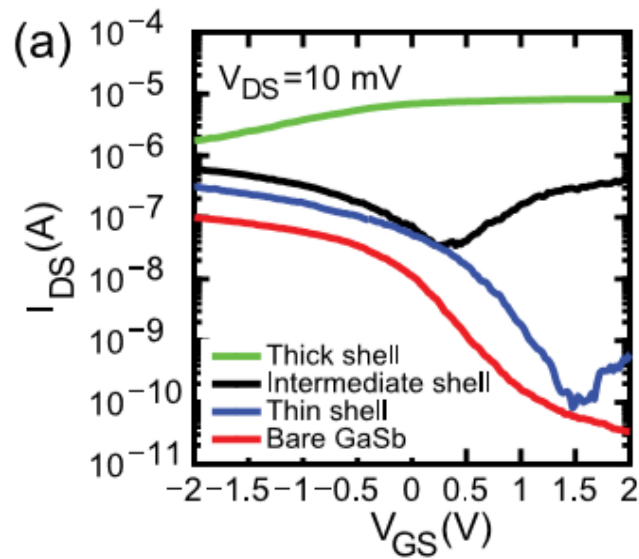
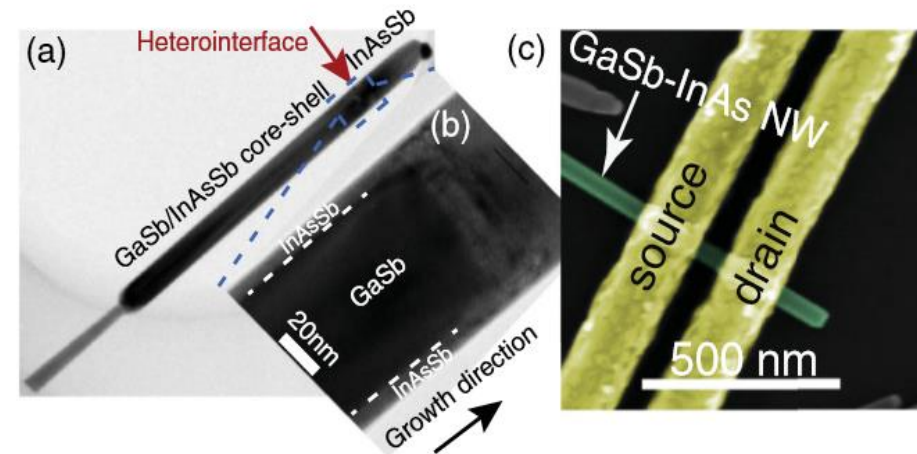
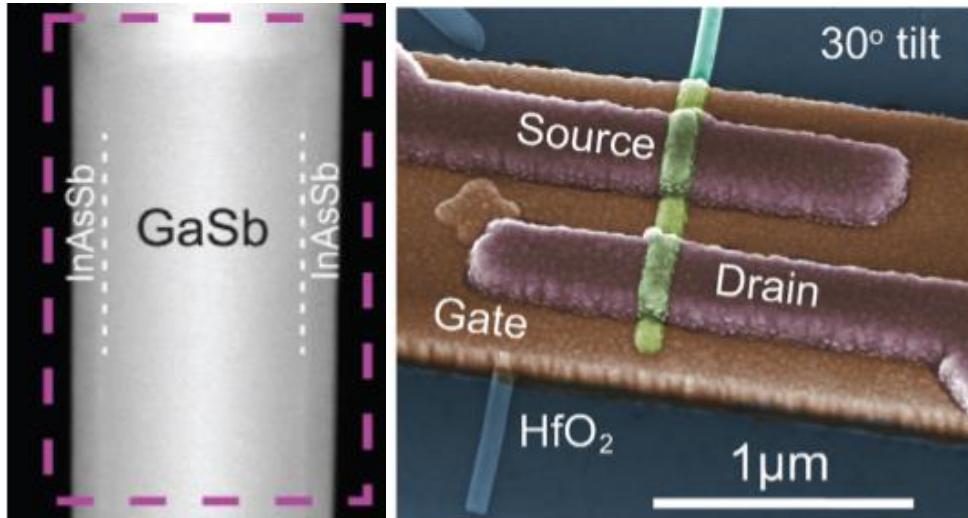
- 
- *Where we are..*
  - *Experimental results*
  - *Device Structure*
  - *InAs/InP/GaSb core-dual shell NWs; application*
  - *InAs/GaSb heterostructure; application*
  - *Broken-gap; Negative differential resistance*
  - *III-V heterostructures NW with broken gap*

- Inter-band tunneling without a barrier
- High current drive
- Future exciton- and spin-physics studies

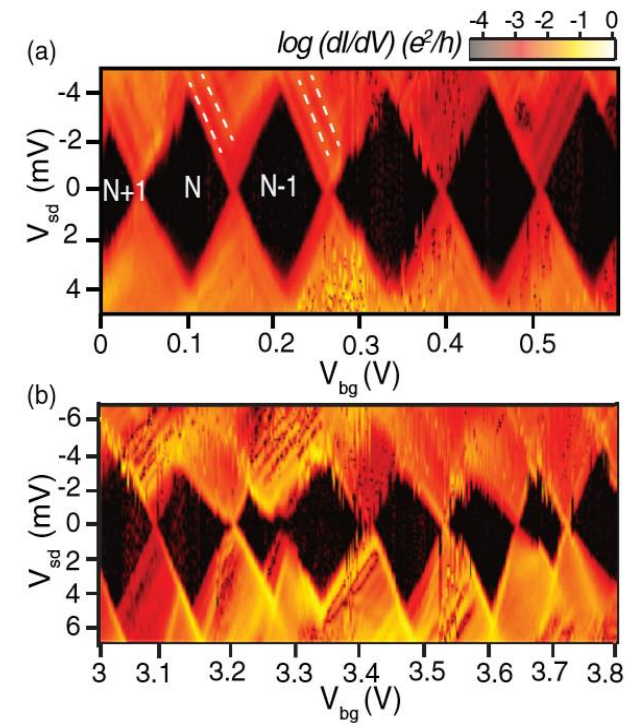


T. Reiger et al. Nanoscale, 2015





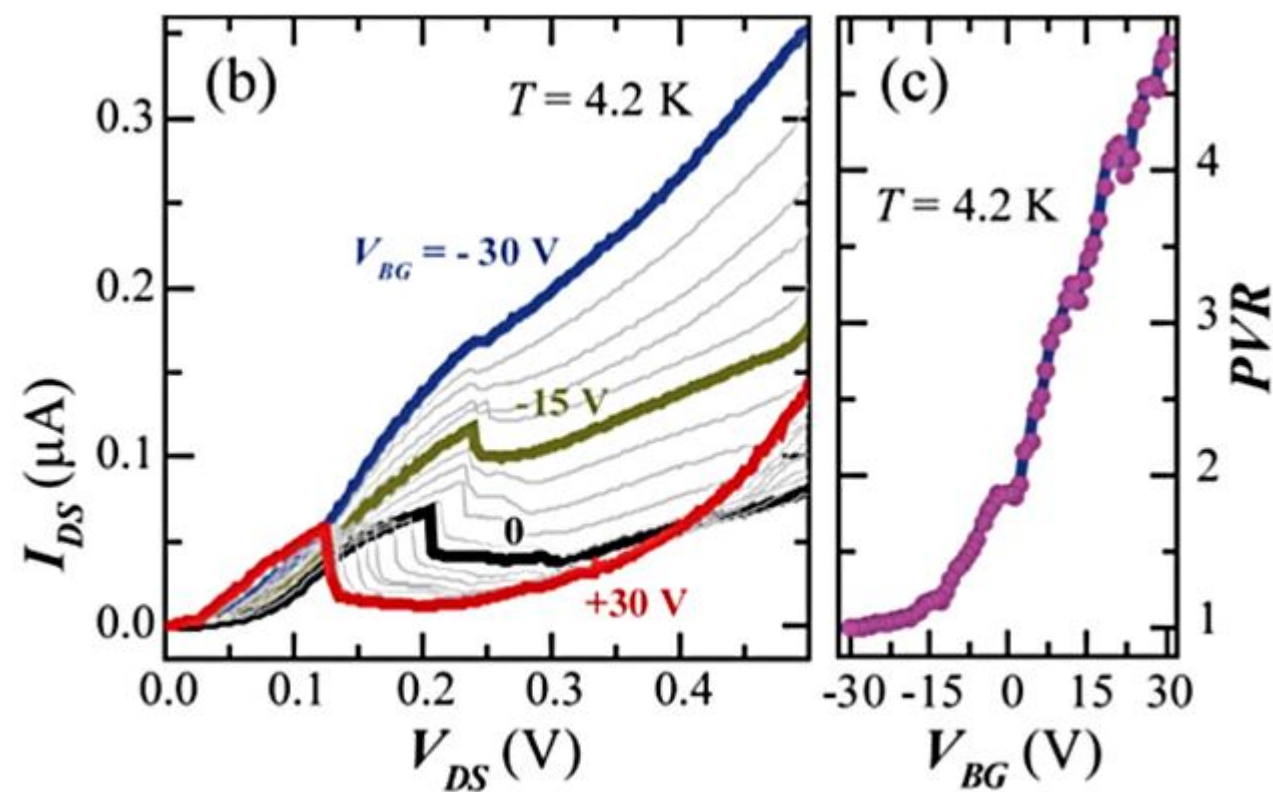
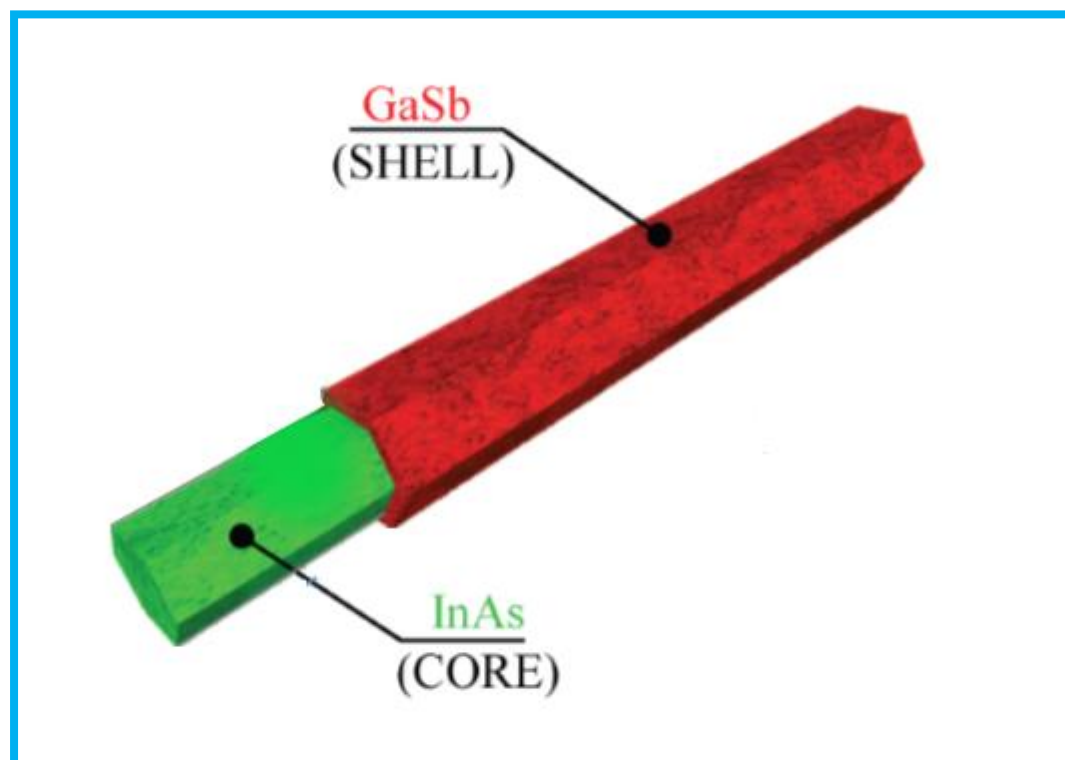
Appl. Phys. Lett. 101, 103501 (2012)



Phys. Rev. B 91, 161301(R) (2015)

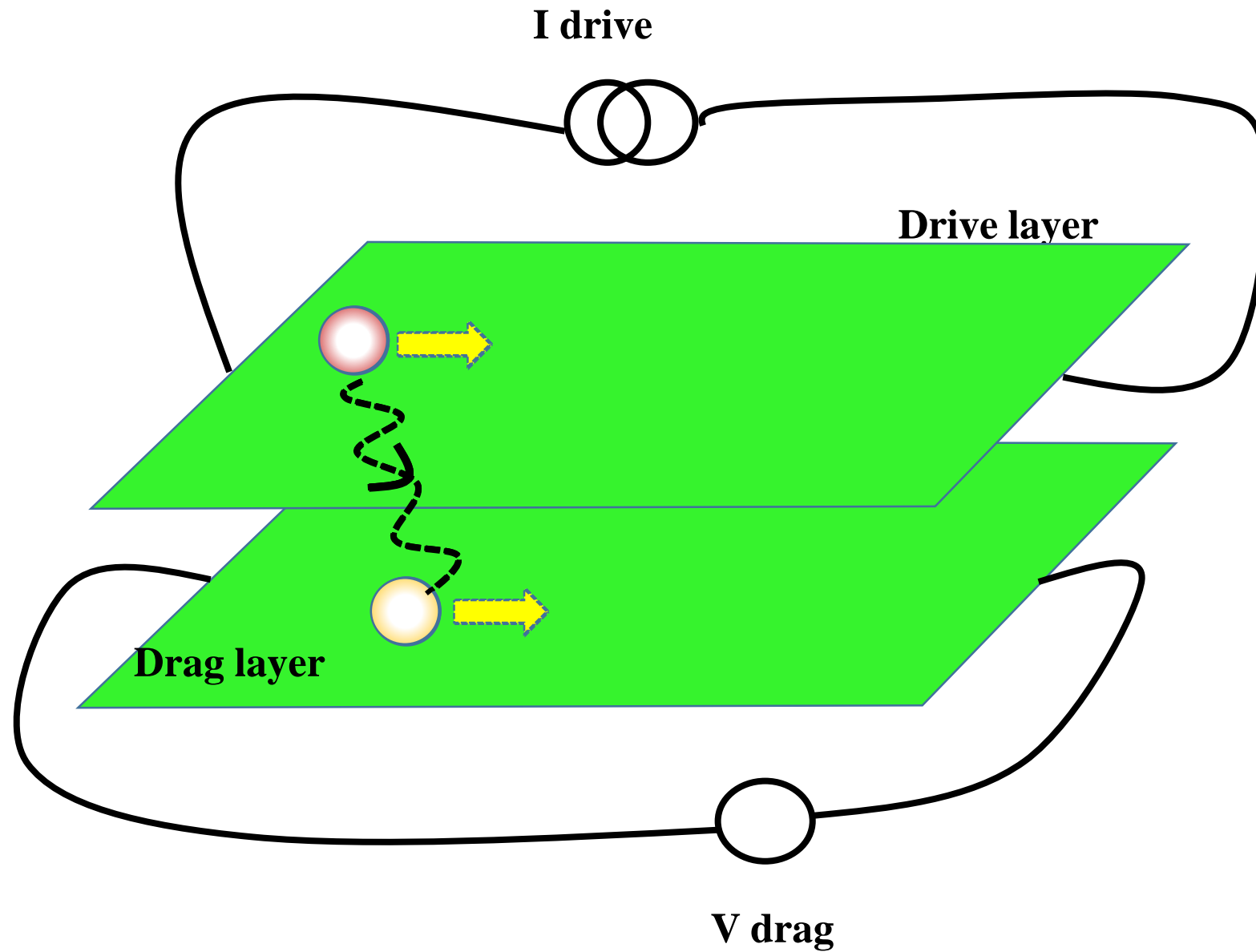
## Tunable Esaki Effect in Catalyst-Free InAs/GaSb Core–Shell Nanowires

M. Rocci,<sup>\*,†</sup> F. Rossella,<sup>\*,†</sup> U. P. Gomes,<sup>†</sup> V. Zannier,<sup>†</sup> F. Rossi,<sup>‡</sup> D. Ercolani,<sup>†</sup> L. Sorba,<sup>†</sup> F. Beltram,<sup>†</sup> and S. Roddaro<sup>\*,†</sup>

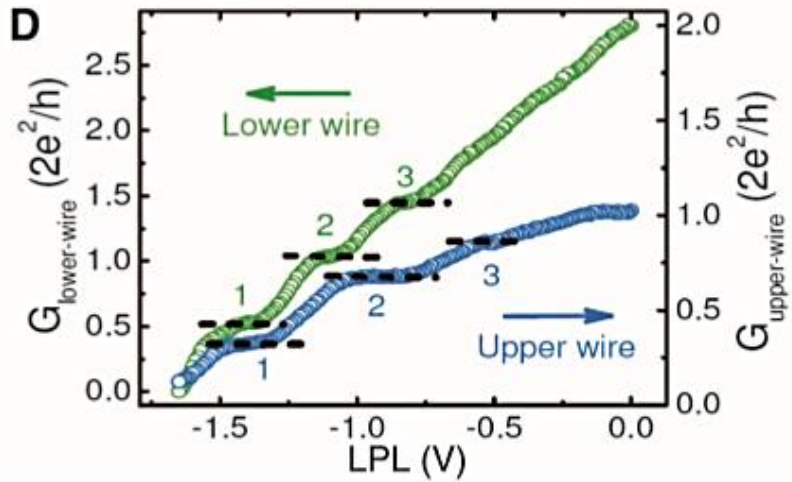
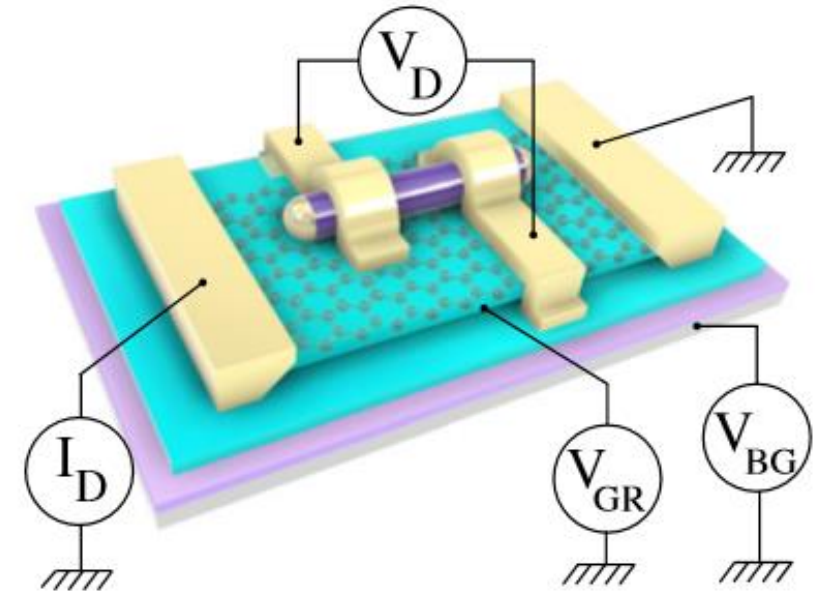
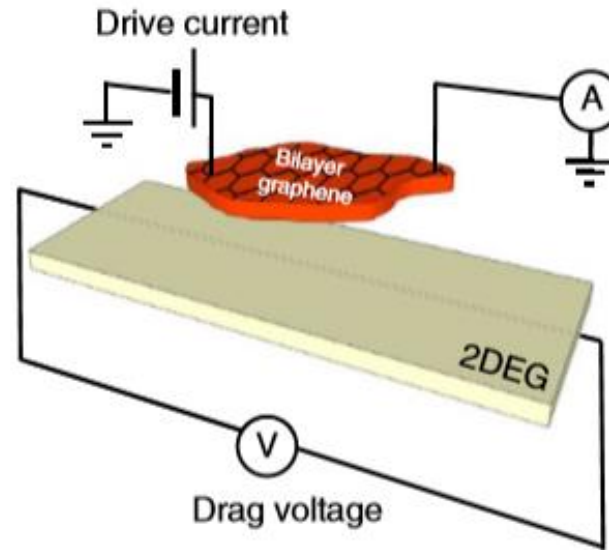
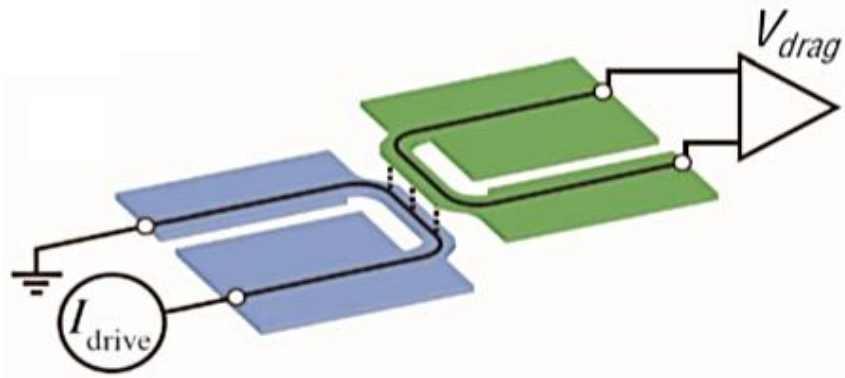


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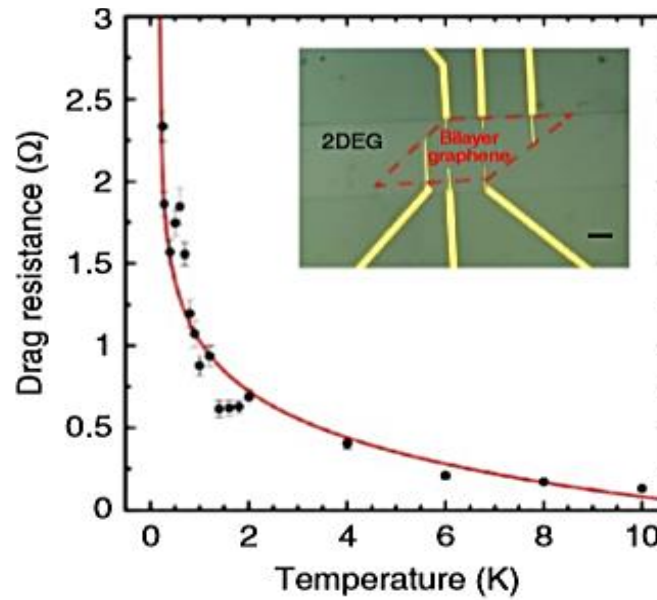
# Coulomb drag systems



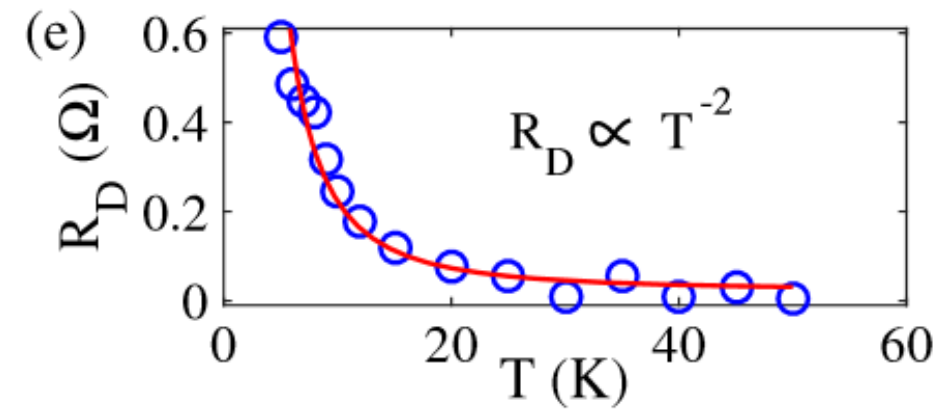
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Science, 343, 632 (2014)

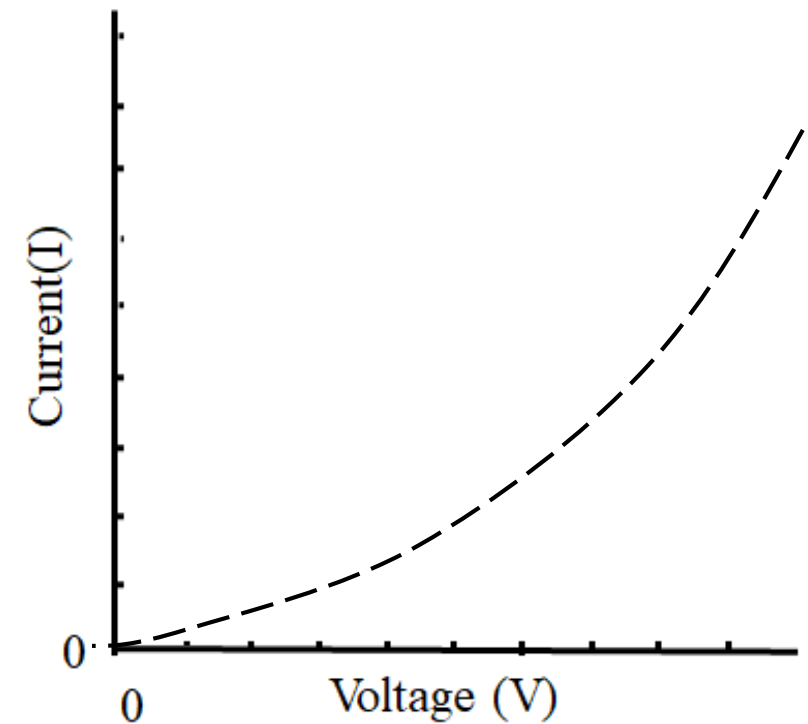
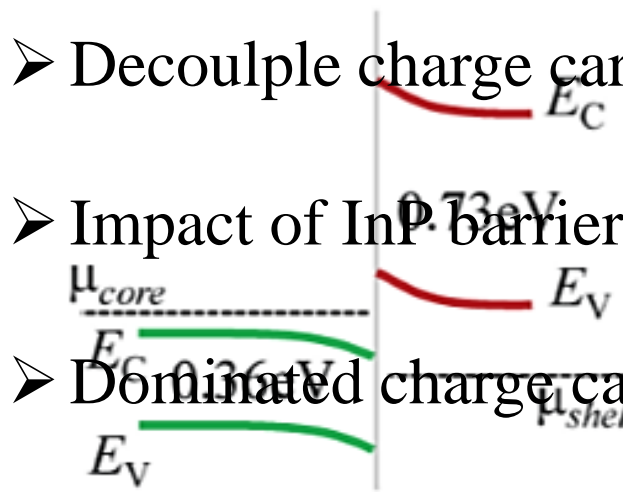
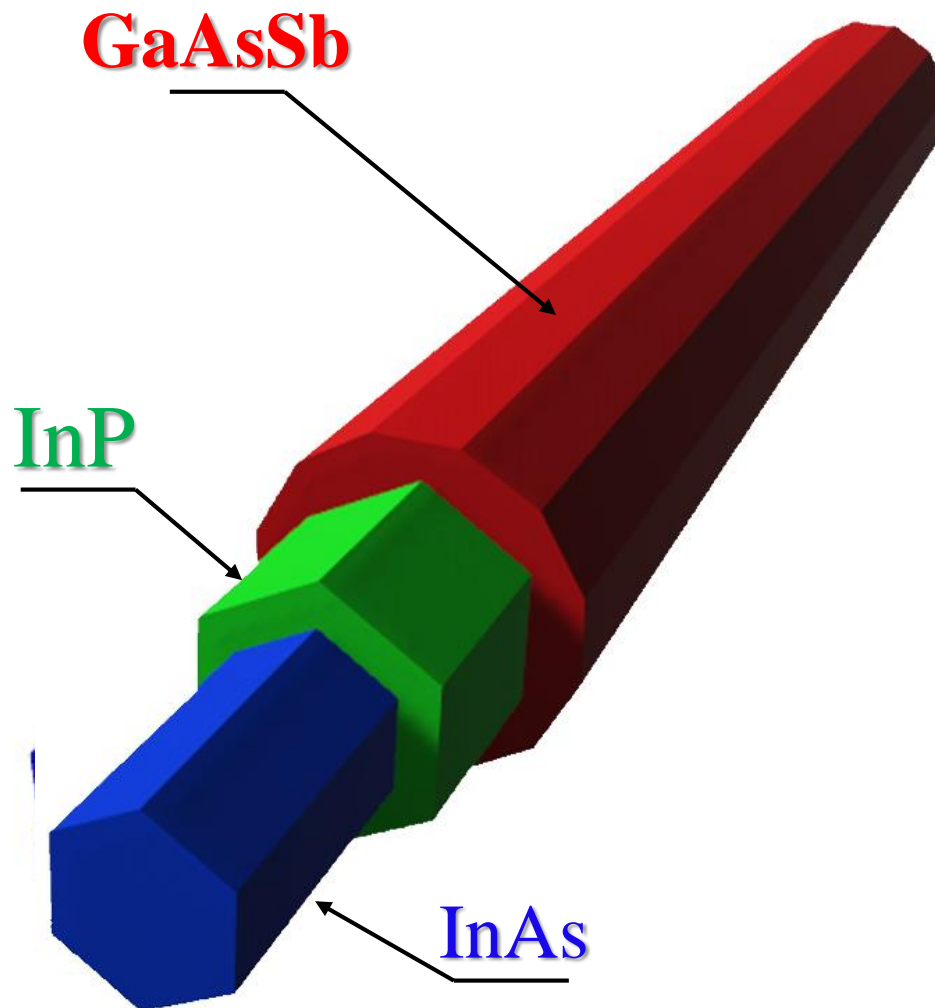


Nature Com. 5, 5824 (2014)



Phys. Rev. Let. 124, 116803 (2020)

- Decouple charge carriers
- Impact of InP barrier
- Dominated charge carrier in each channel.

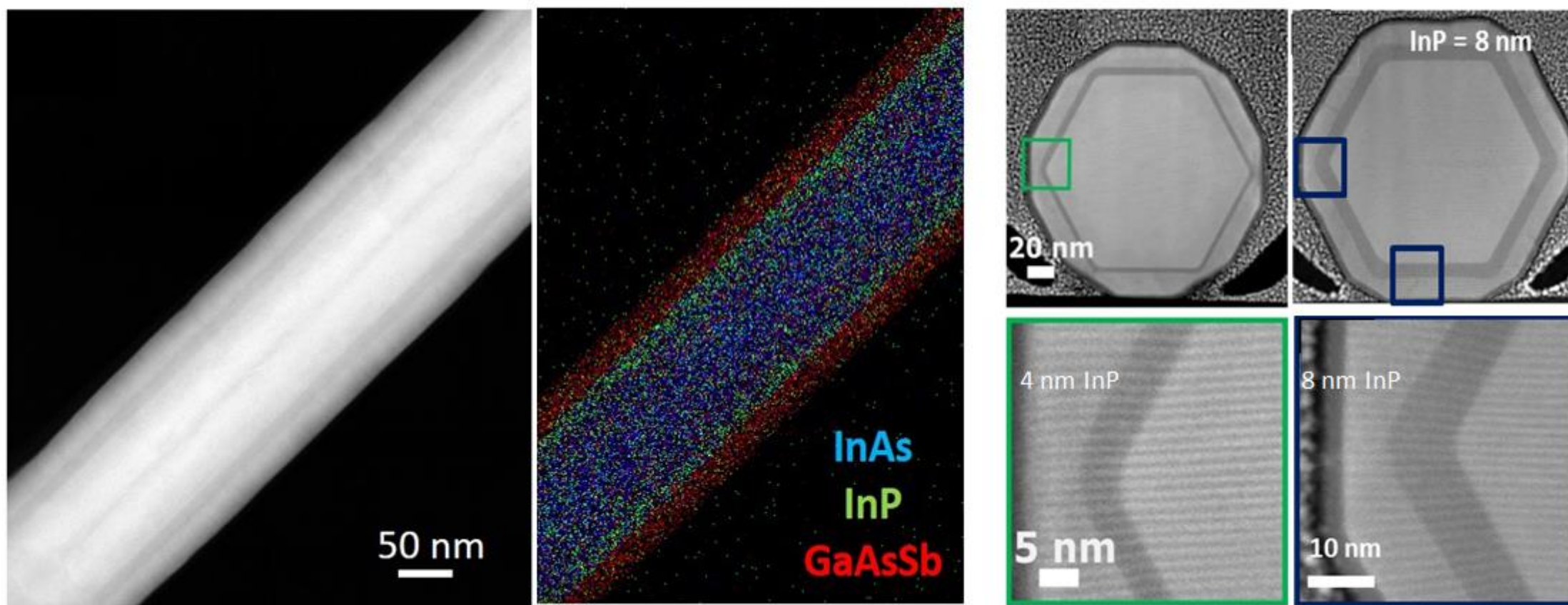


M. Rocci, et al. Nanoletter (2016)



# Growth and Strain Relaxation Mechanisms of InAs/InP/GaAsSb Core-Dual-Shell Nanowires

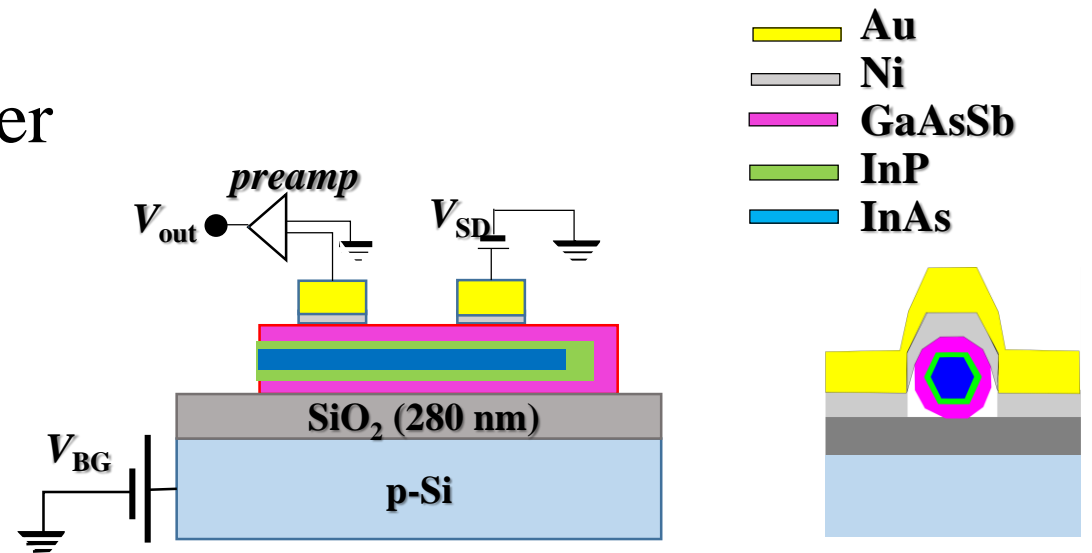
Omer Arif, Valentina Zannier,\* Ang Li, Francesca Rossi, Daniele Ercolani, Fabio Beltram, and Lucia Sorba



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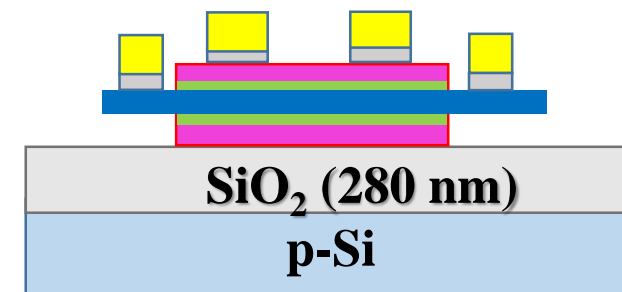
## ➤ Shell-Shell configuraion

Finding the practical thickness of InP barrier

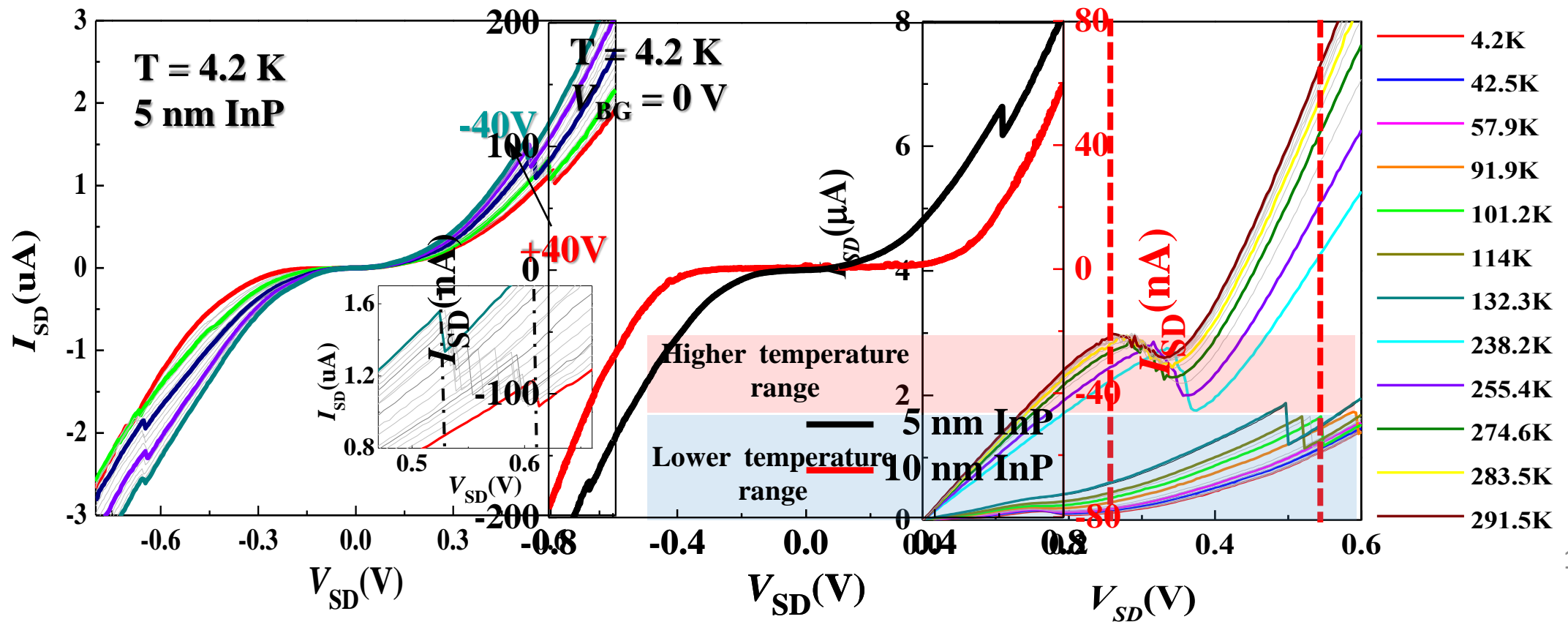
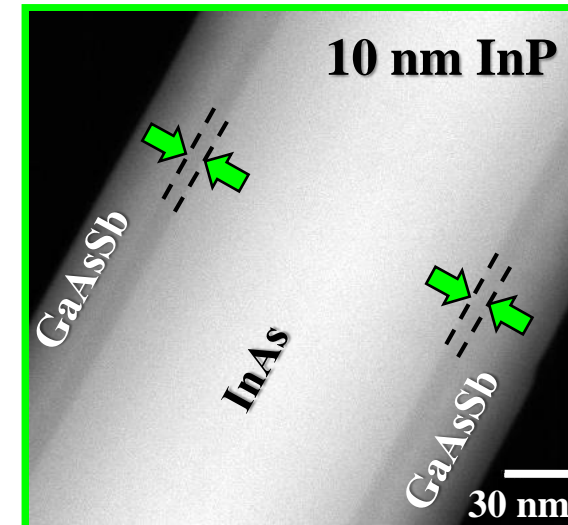
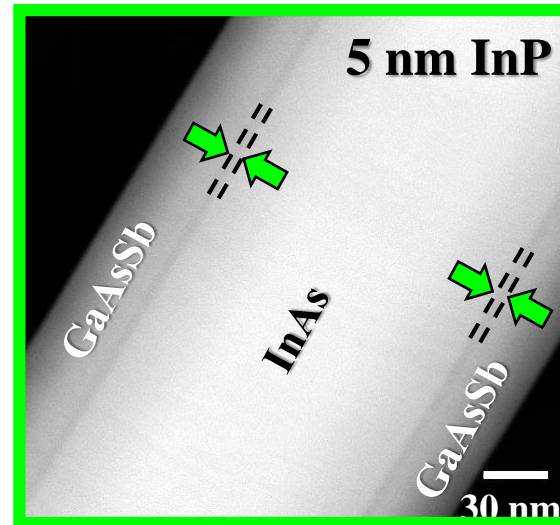
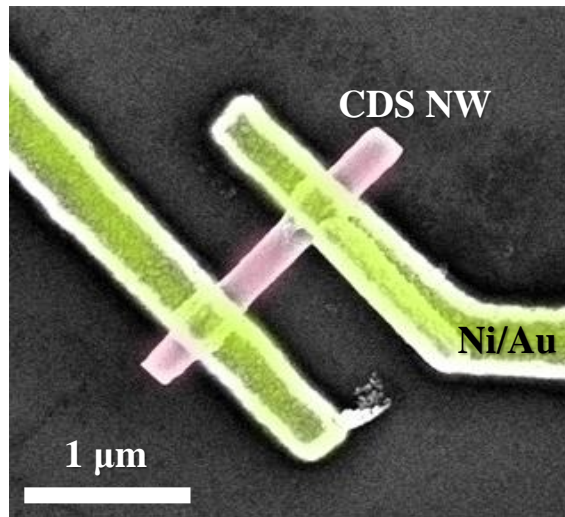


## ➤ Multi-terminal core-shell devices

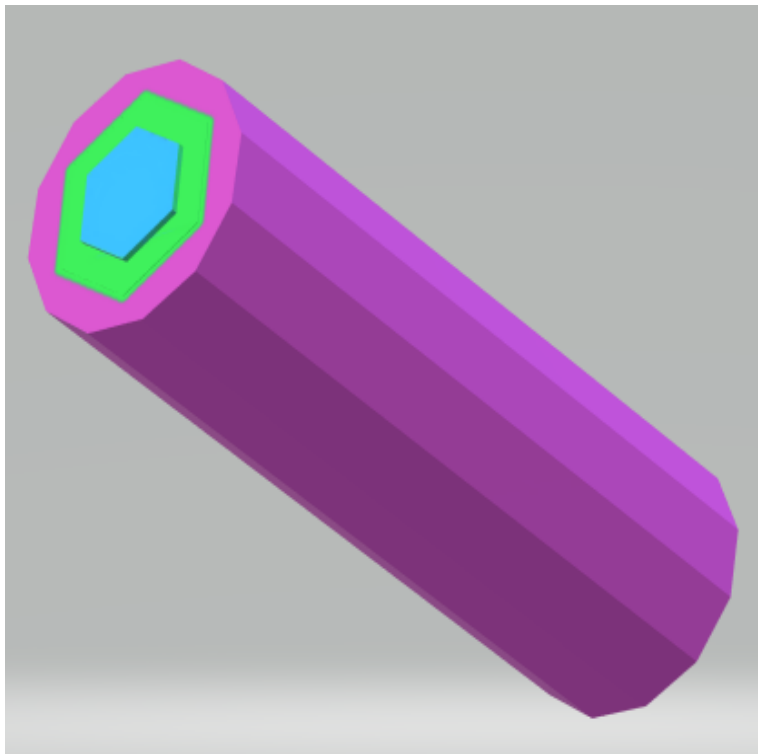
Studying the impact of InP barrier



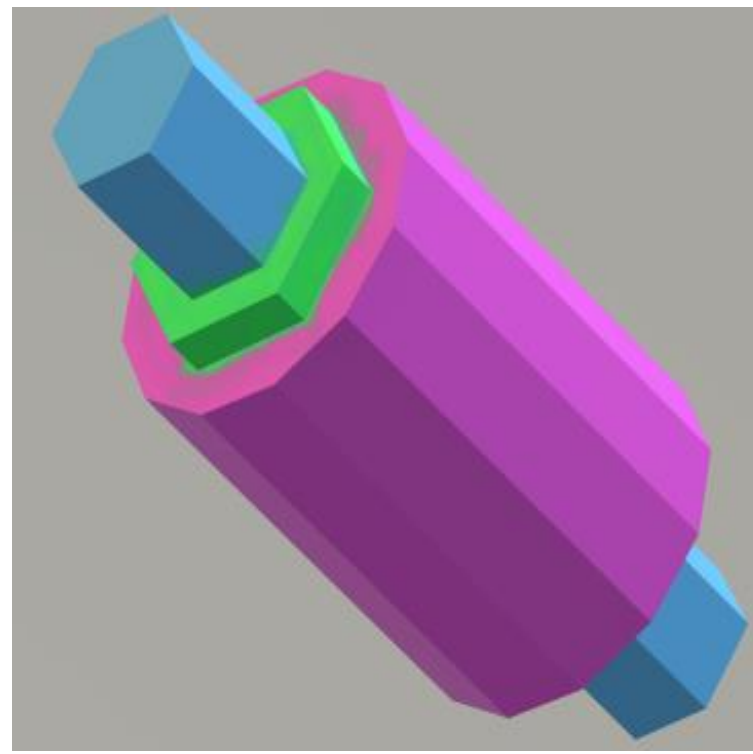
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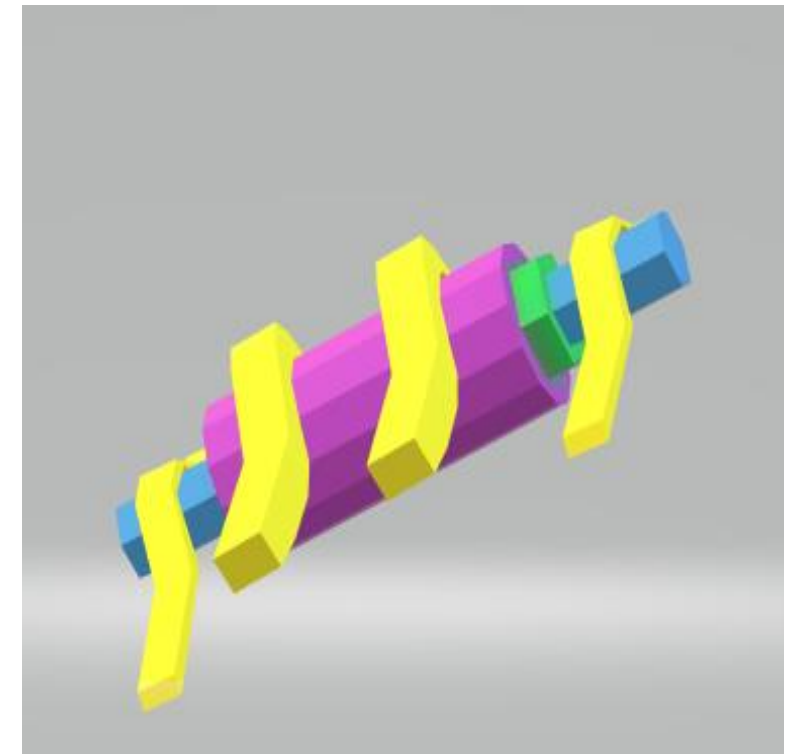
**CDS NW**



**Etched CDS NW**



**Multiterminal device**

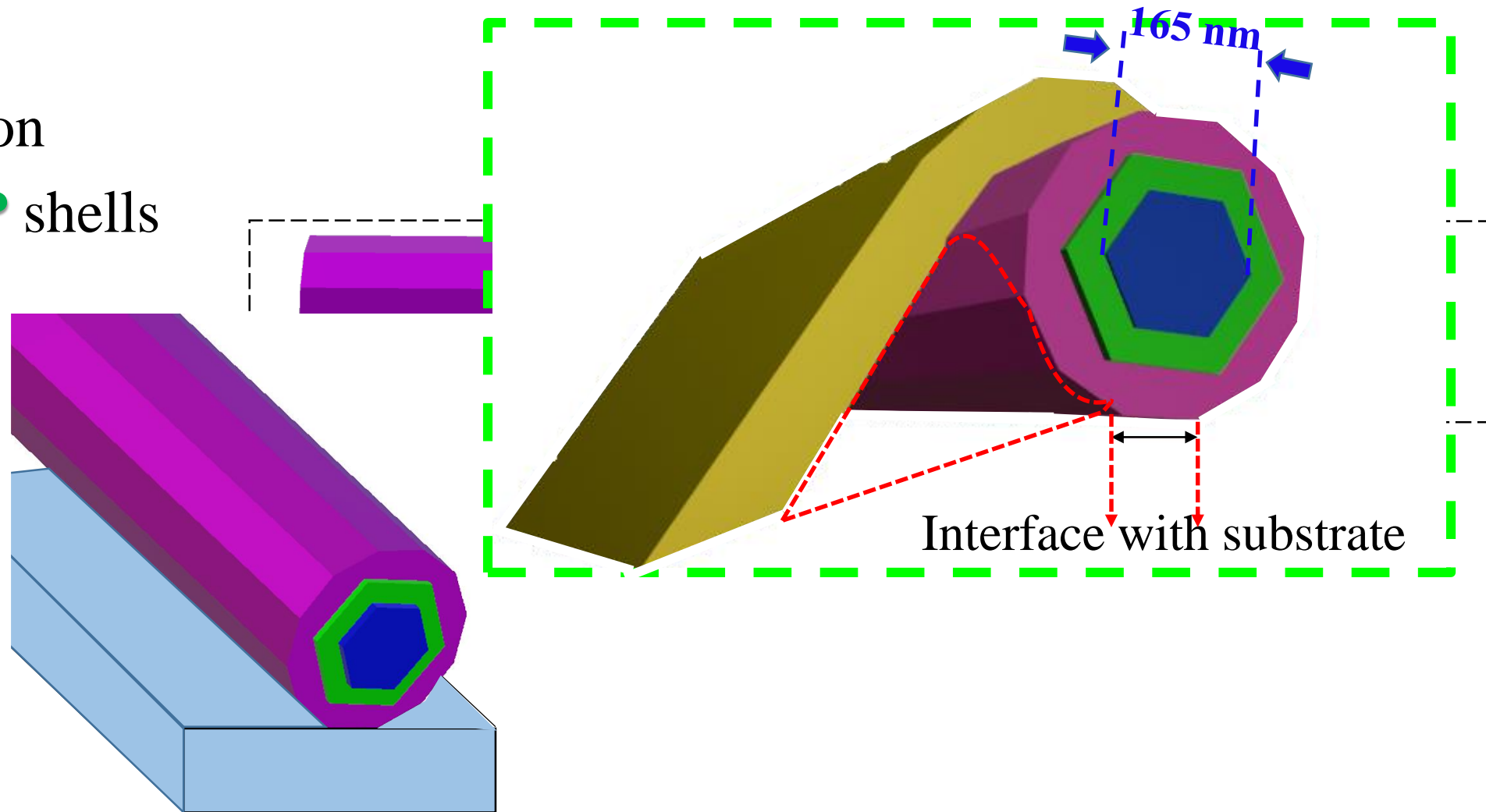


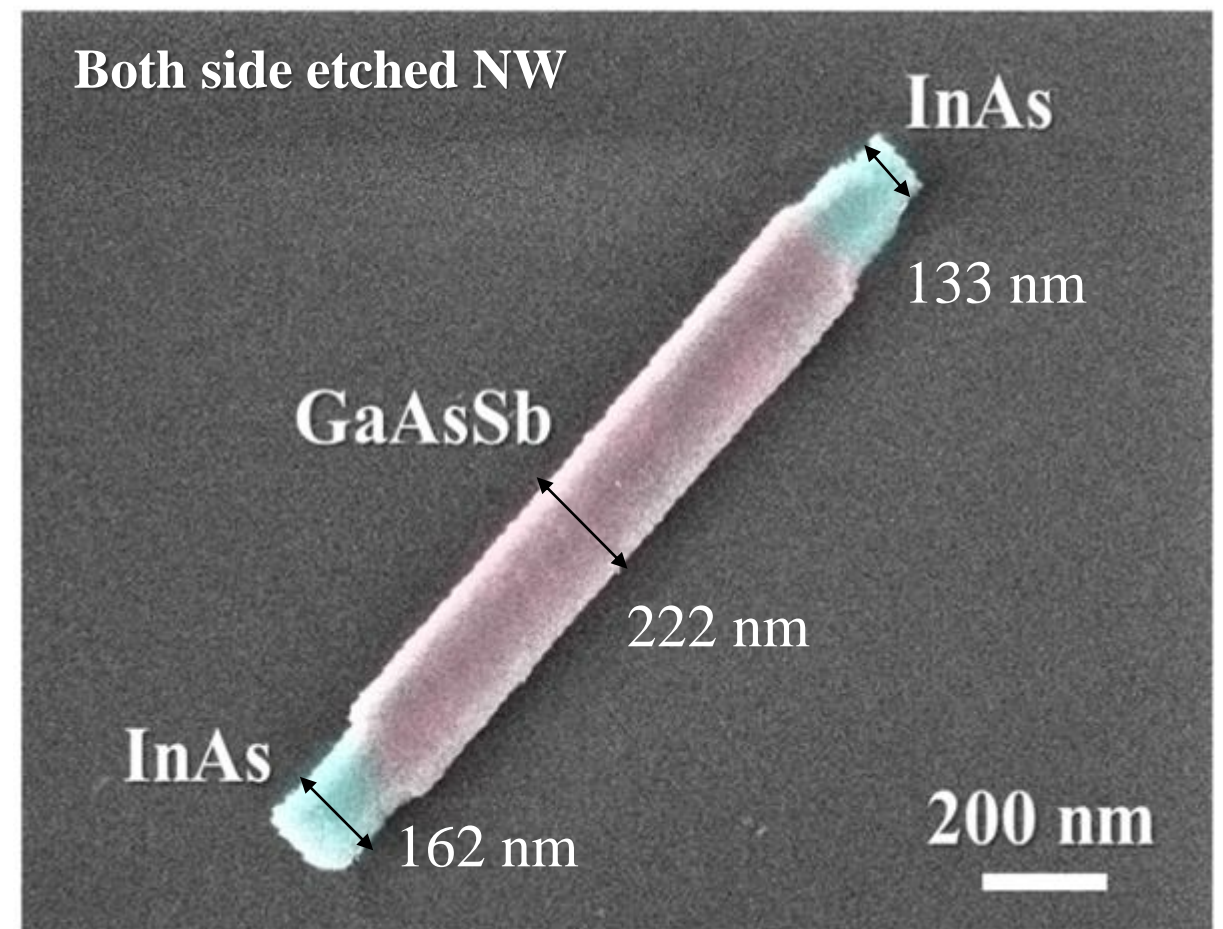
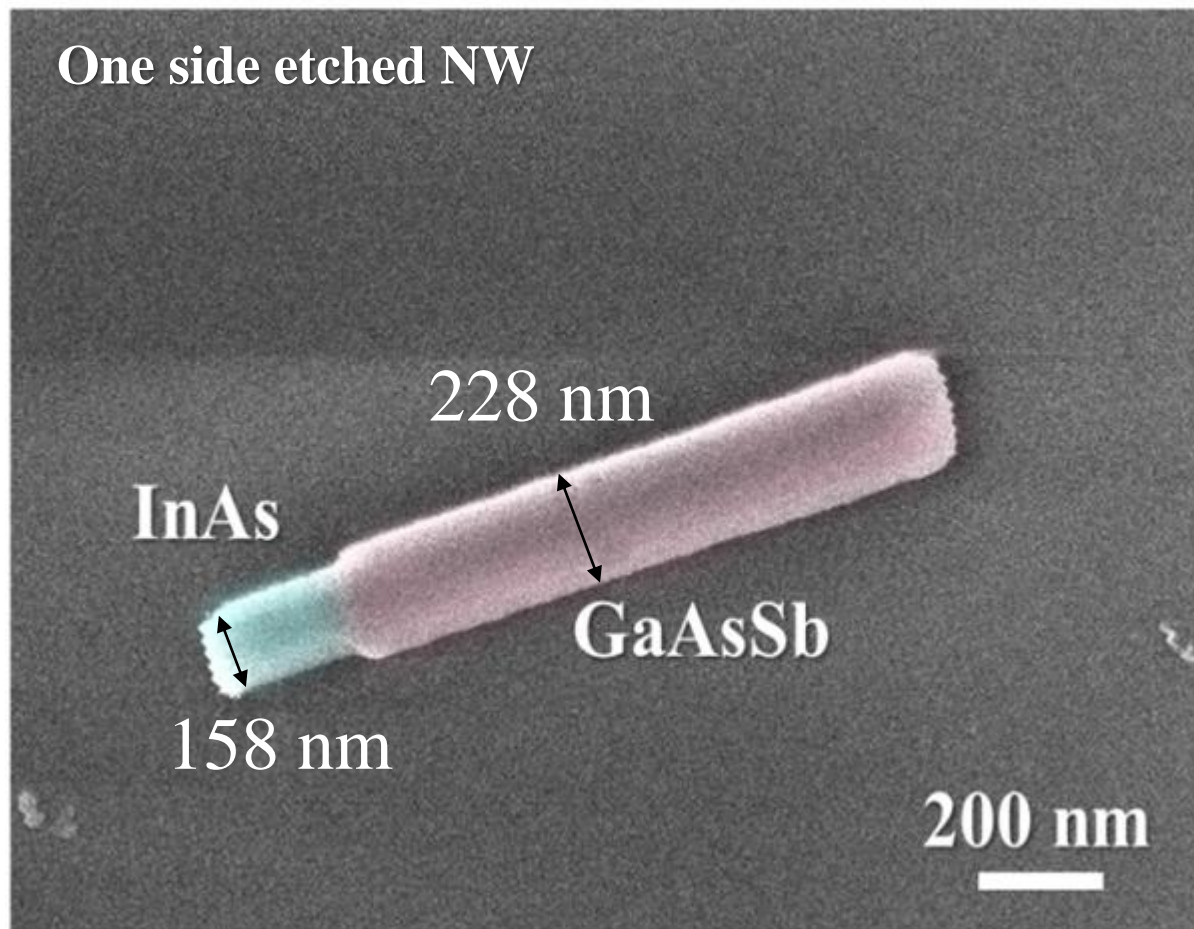
➤ Selective area etching from GaAsSb and InP

➤ Etchant calibration

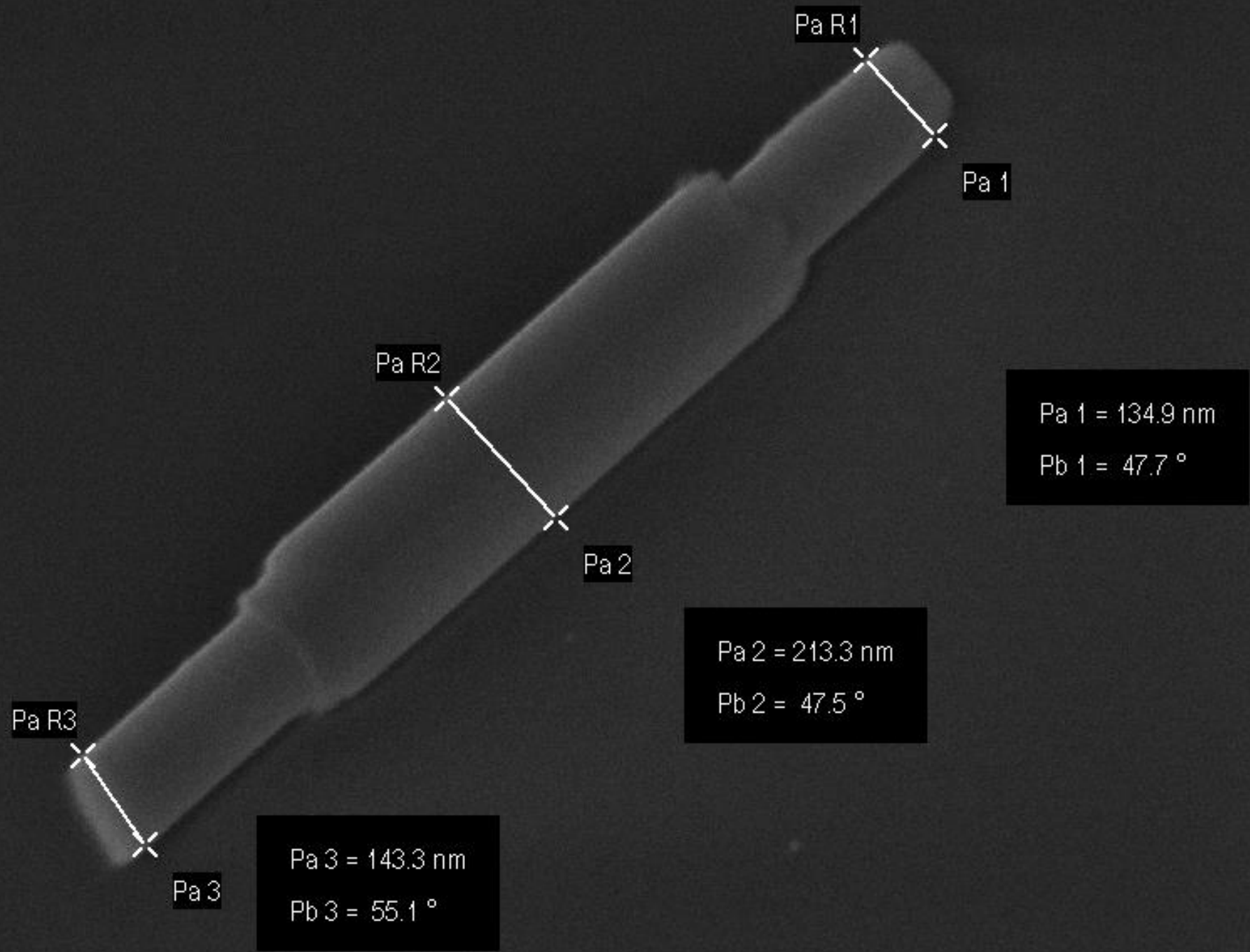
**GaAsSb** and **InP** shells

➤ NW geometry





# Selective area etching CDS Nanowire



Mag = 50.38 K X  
200 nm

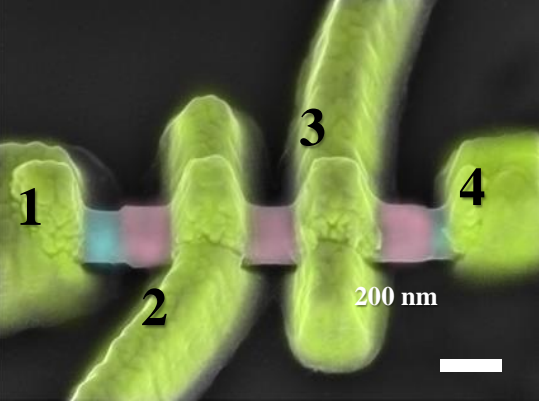
WD = 4.9 mm EHT = 5.00 kV 96 pA  
High Resolution tilt = 0.0 ° -38.0 pA

Signal A = InLens Date : 7 Nov 2019  
ESB Grid is = 1495 V Time : 17:25:52

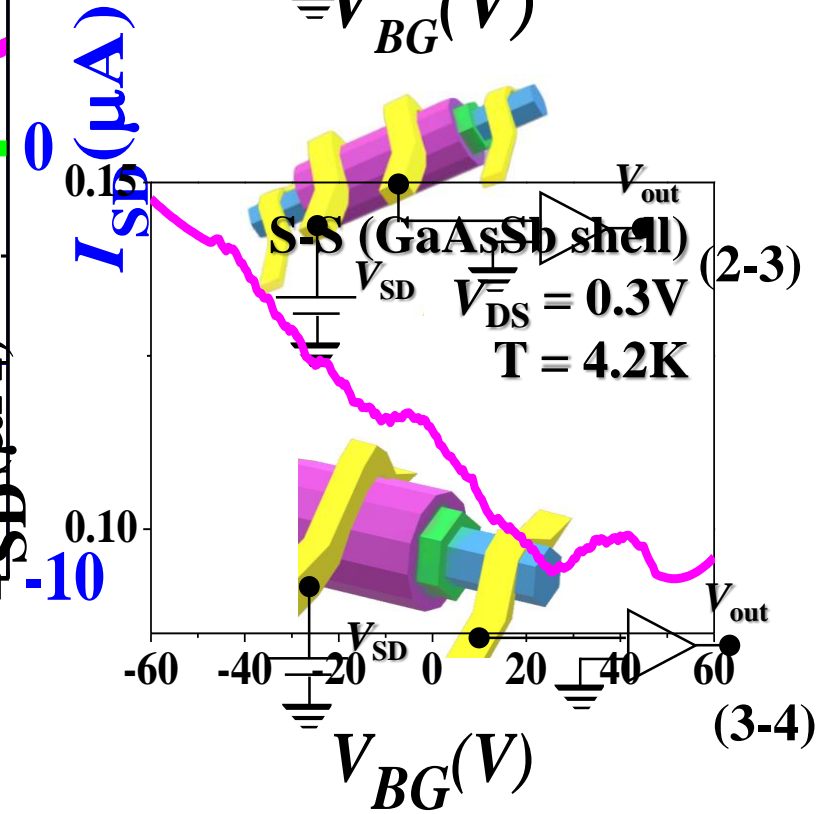
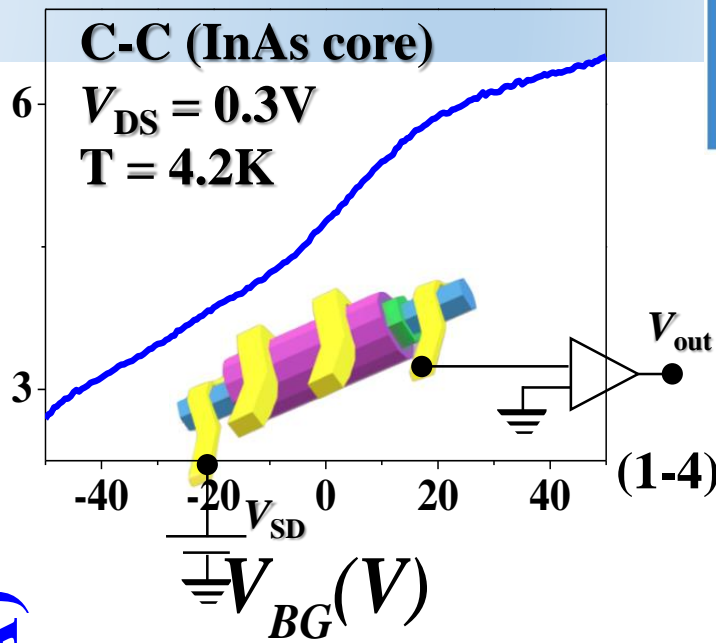
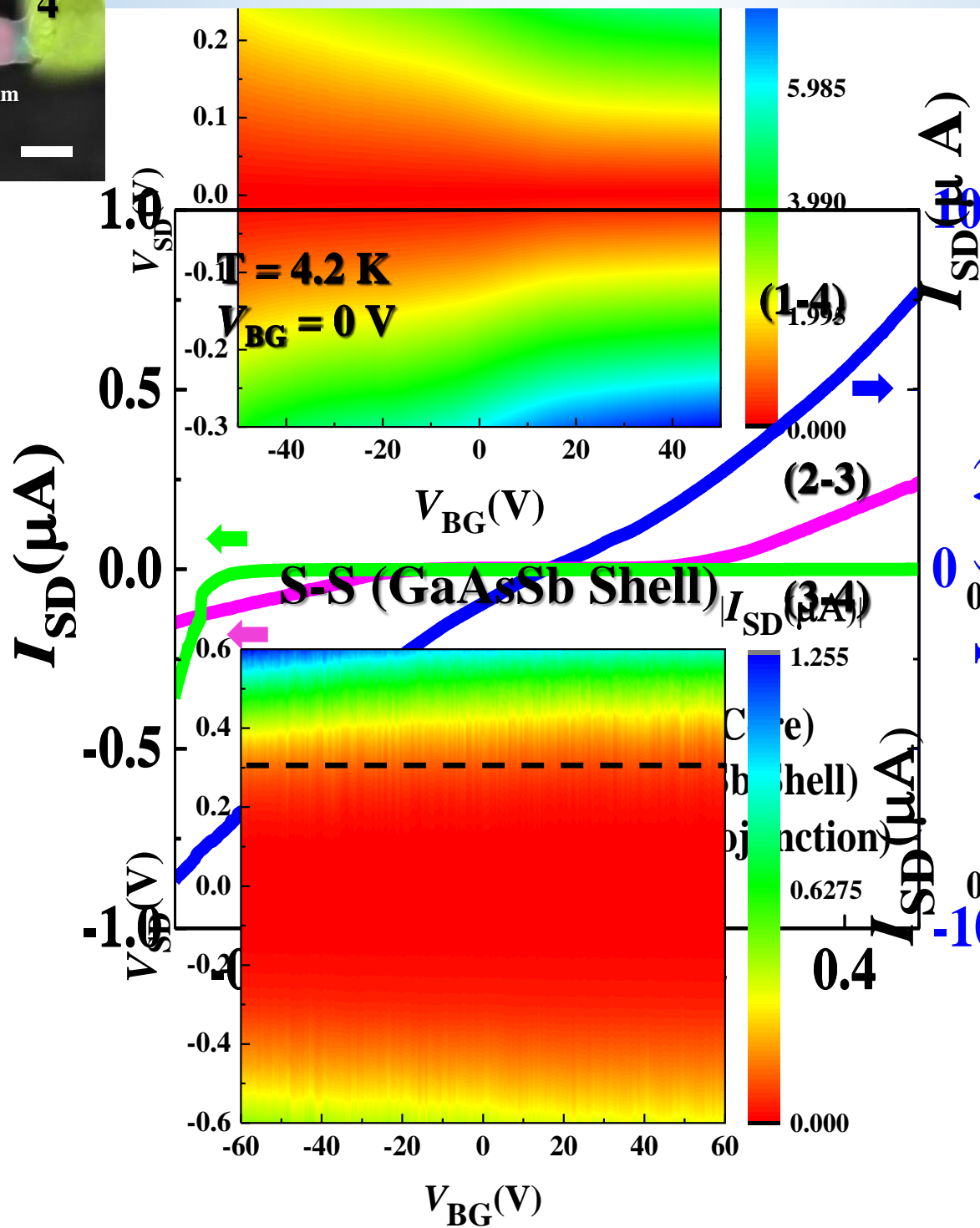
# *Multiterminal Core-Shell device*





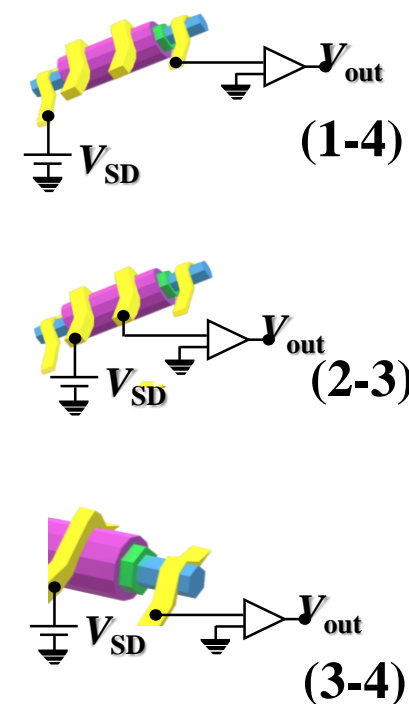
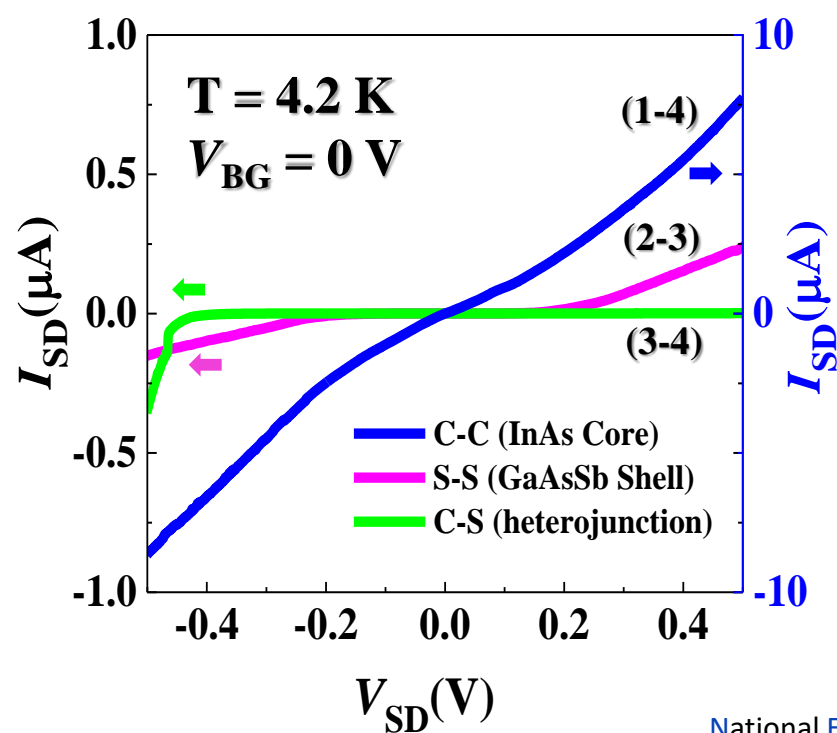
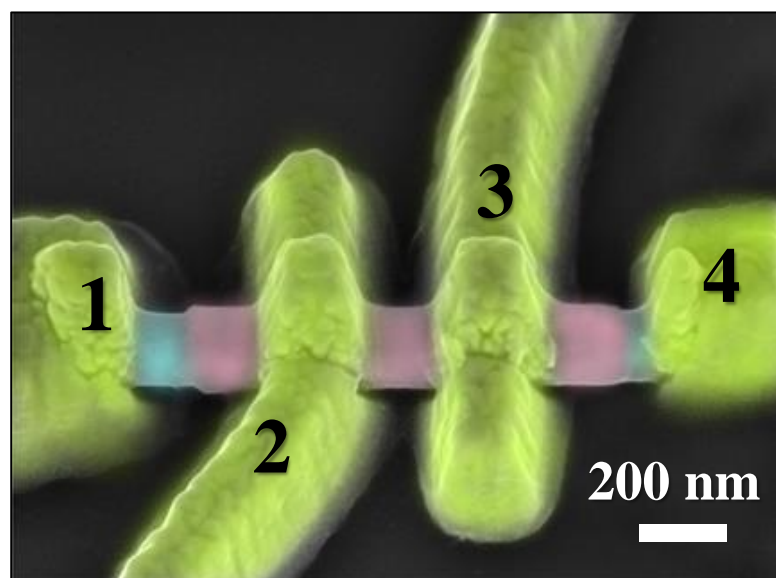


# Impact of InP barrier



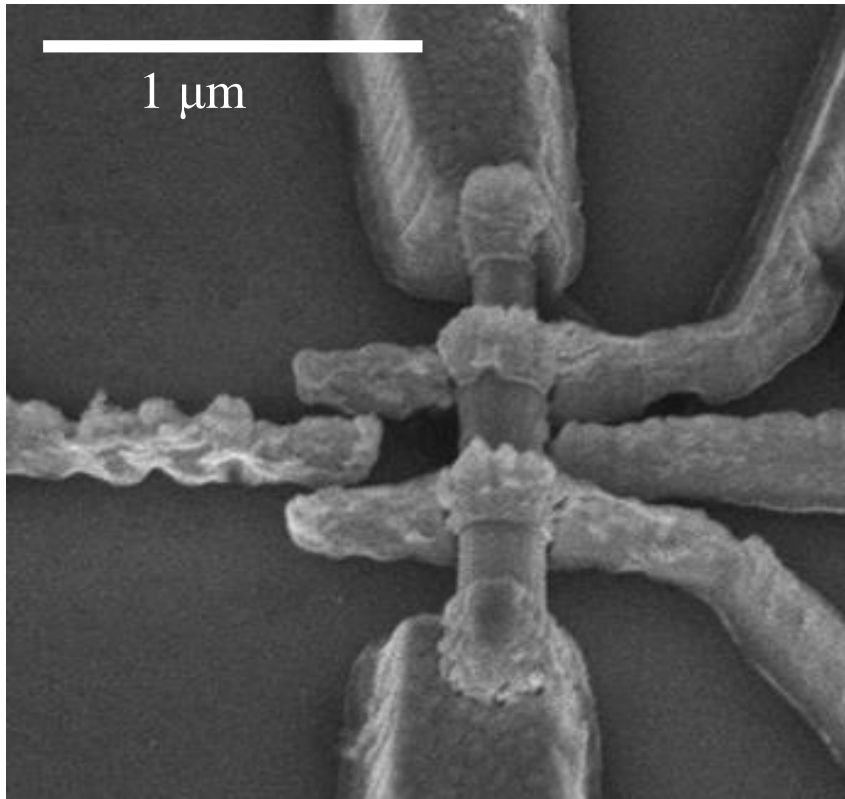
# Electrical probing of carrier separation in InAs/InP/GaAsSb core-dualshell nanowires

Sedighe Salimian<sup>1</sup> (✉), Omer Arif<sup>1</sup>, Valentina Zannier<sup>1</sup>, Daniele Ercolani<sup>1</sup>, Francesca Rossi<sup>2</sup>, Zahra Sadre Momtaz<sup>1</sup>, Fabio Beltram<sup>1</sup>, Sefano Roddaro<sup>1,3</sup>, Francesco Rossella<sup>1</sup> (✉), and Lucia Sorba<sup>1</sup>



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# Where we are..



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# Graphene/ultrathin-Si<sub>3</sub>N<sub>4</sub> heterostructure device

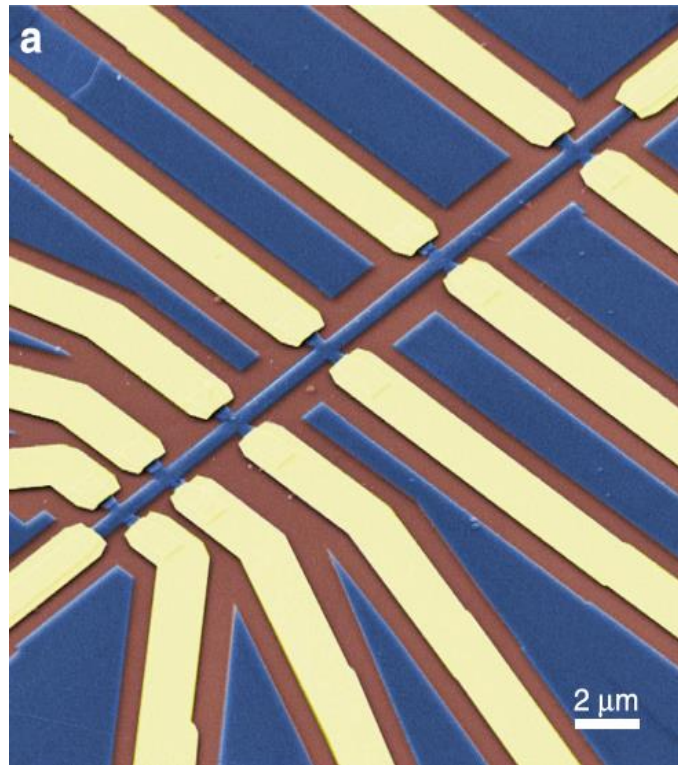
National Enterprise for nanoScience and nanoTechnology

NEST

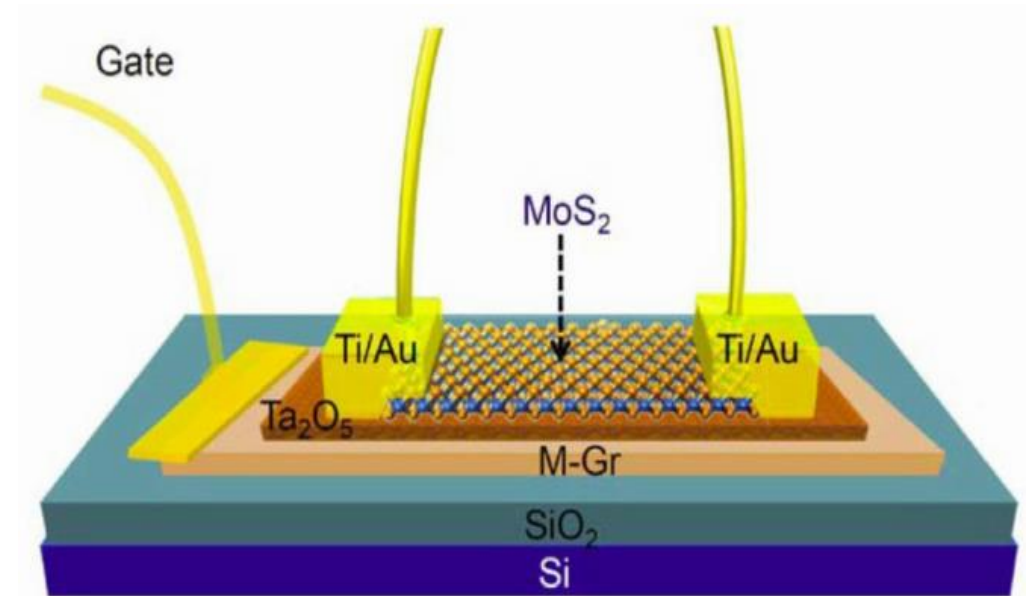
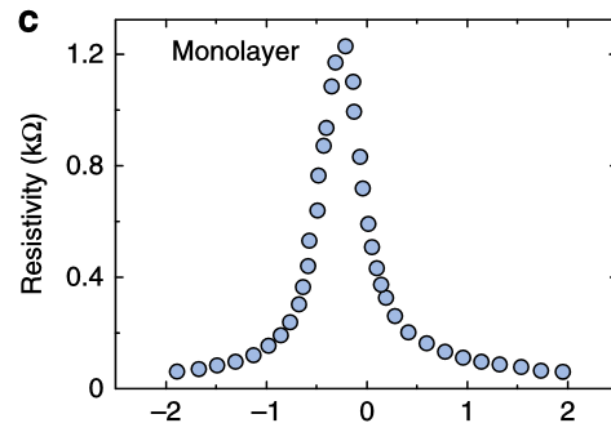
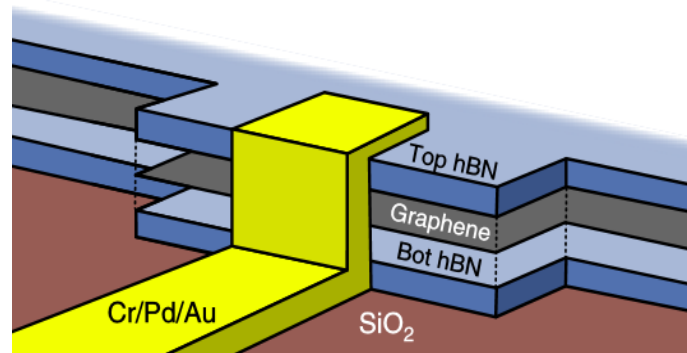
- Why  $\beta$ - $\text{Si}_3\text{N}_4$
- Device structure
- STM on graphene/ $\beta$ - $\text{Si}_3\text{N}_4$  device
- Magneto-transport measurements

# Why high-k Dielectric ?

- ✓ Preserving the intrinsic mobility
- ✓ Minimizing operation voltage



F. Pizzocchero et al. Nature Com. (2016)



B. Chamlagain et al. 2D Mater. (2017)

# Si<sub>3</sub>N<sub>4</sub> Potential

Lattice mismatch (G/Si<sub>3</sub>N<sub>4</sub>)= 3.66 %

ε = 6.6

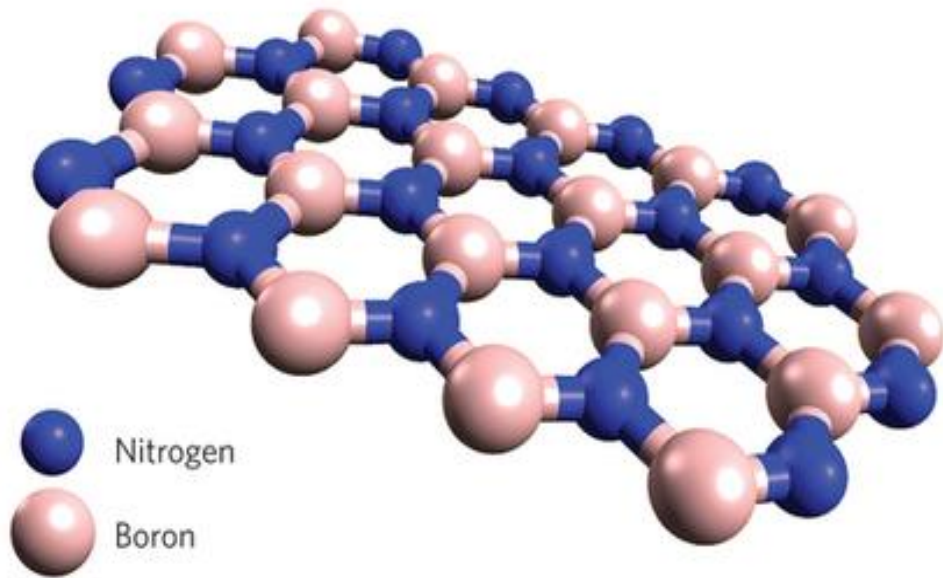
E<sub>g</sub>= 5.3 eV

Lattice mismatch (G/hBN)= 1.8 %

ε = 3 - 4

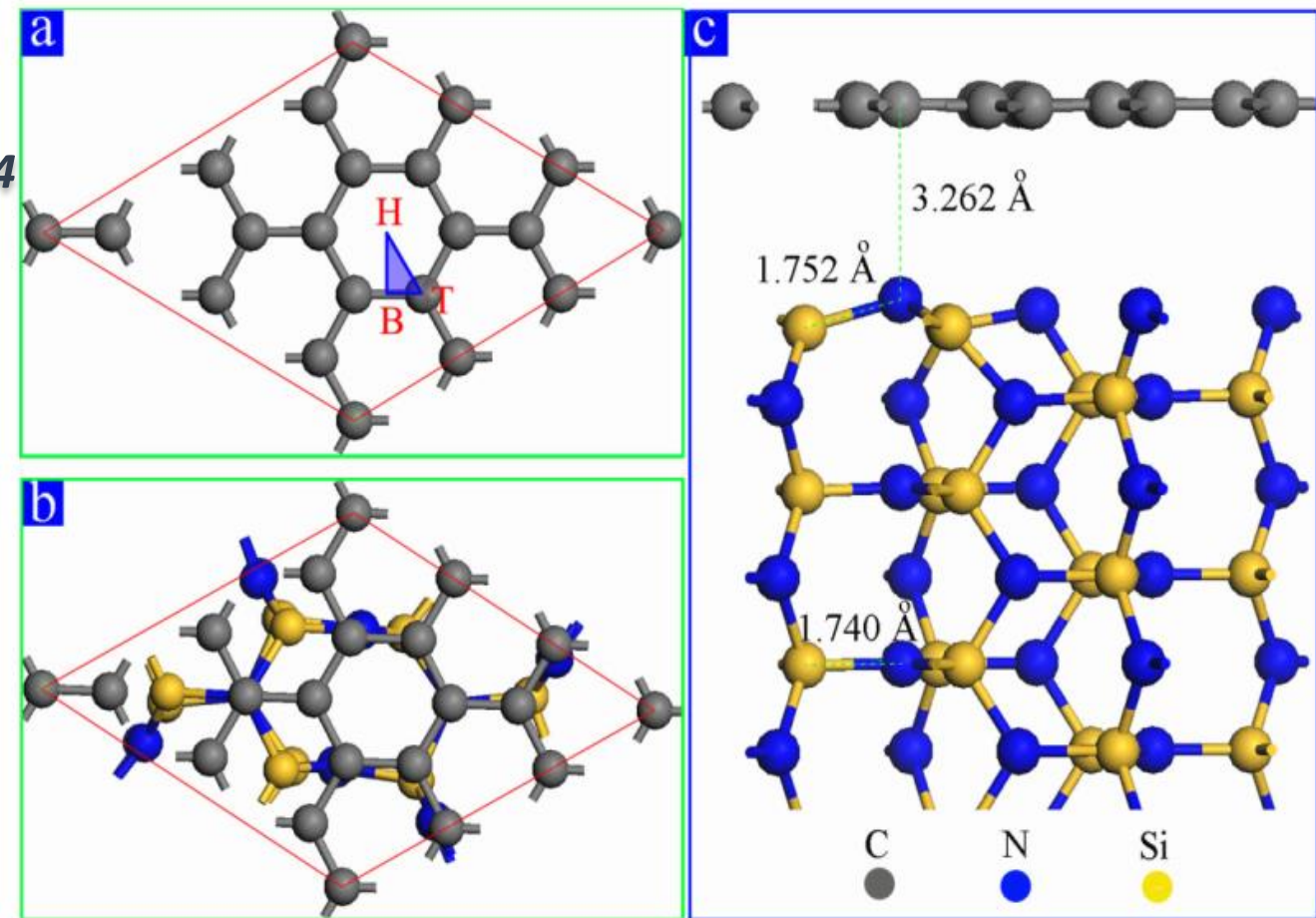
E<sub>g</sub>= 6 eV

**hBN**



*Ttrong et al. Nature Nanotech. (2016)*

**Si<sub>3</sub>N<sub>4</sub>**



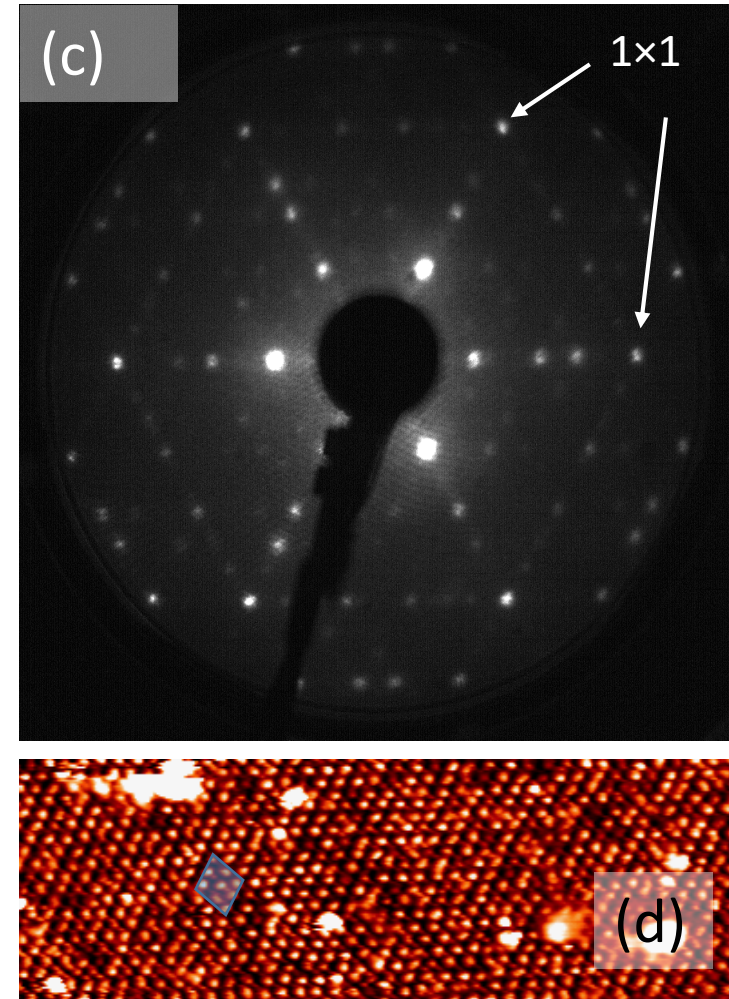
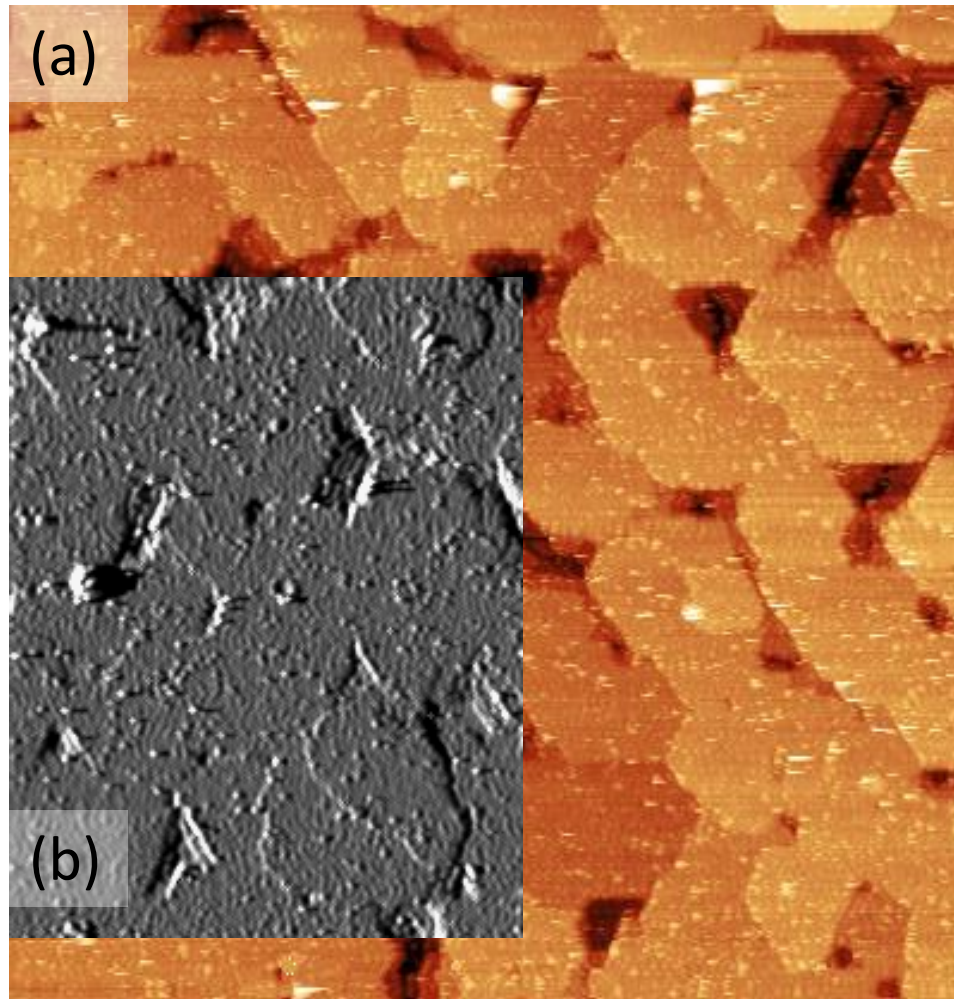
*Yang et al. AIP Advances (2011)*

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500×500 nm<sup>2</sup>

LEED pattern → (8×8) reconstruction

derivative along the x-direction



50×16 nm<sup>2</sup>

Less than 1nm thick large area crystalline  $\beta$ - $\text{Si}_3\text{N}_4$

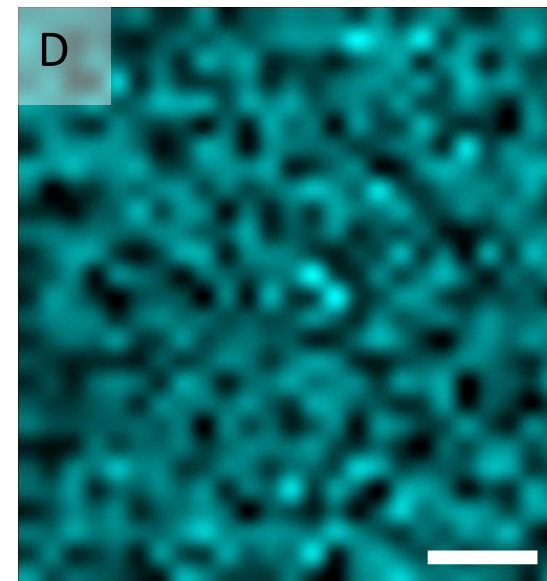
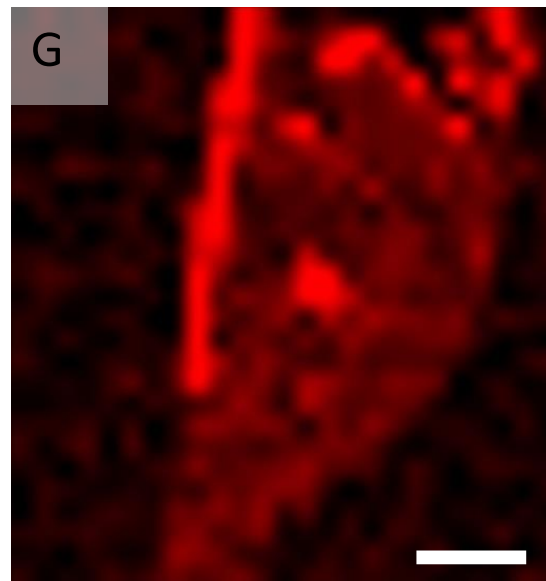
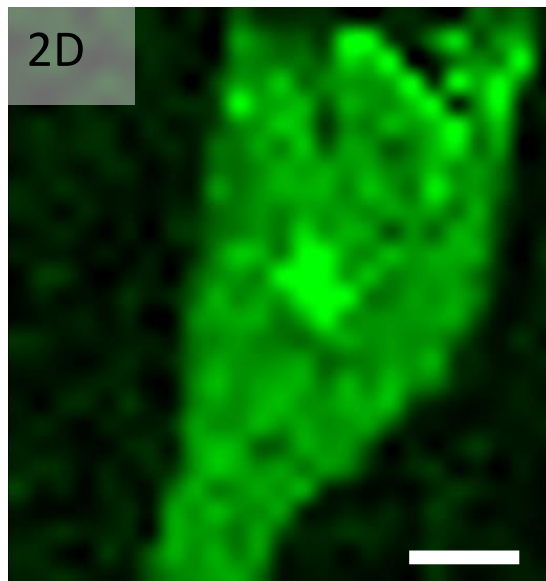
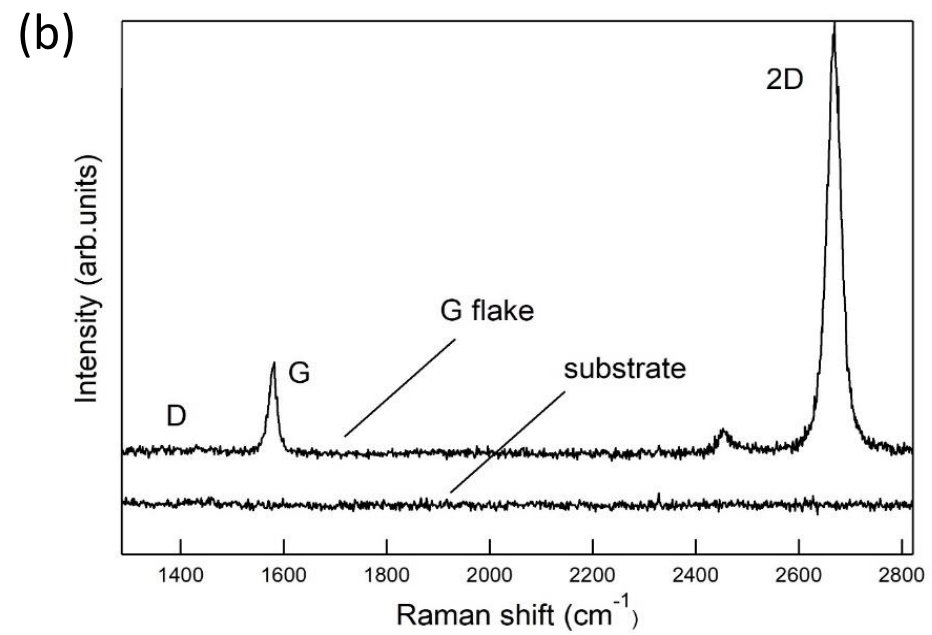
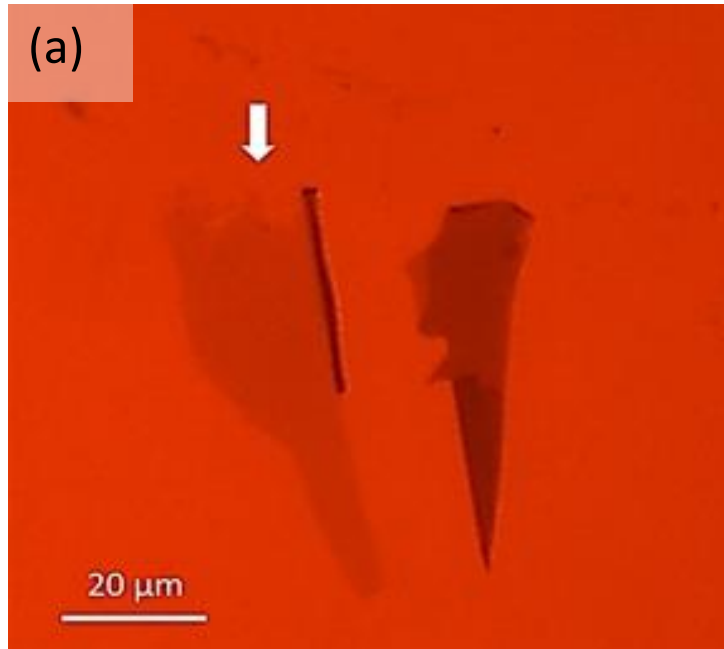
National Enterprise for nanoScience and nanoTechnology



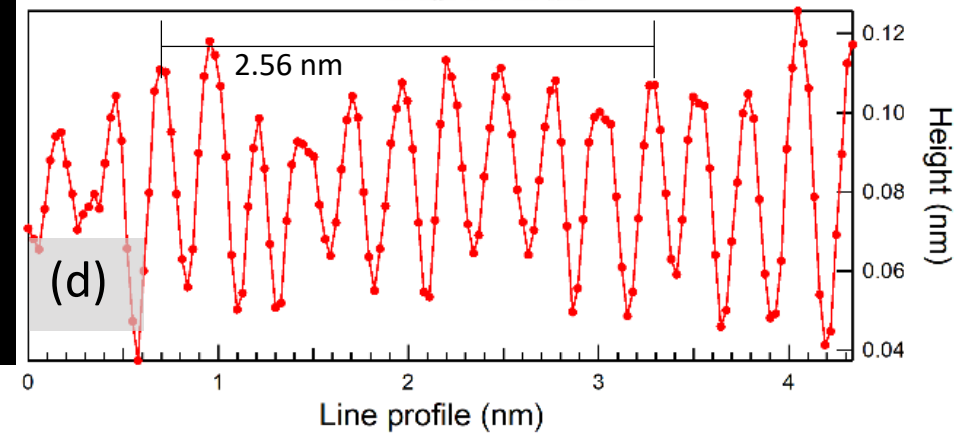
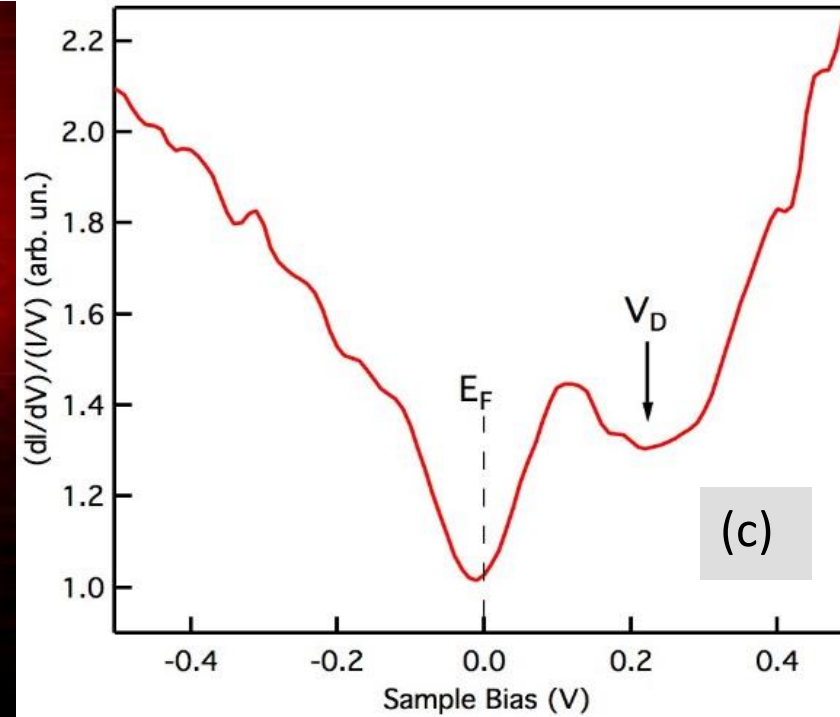
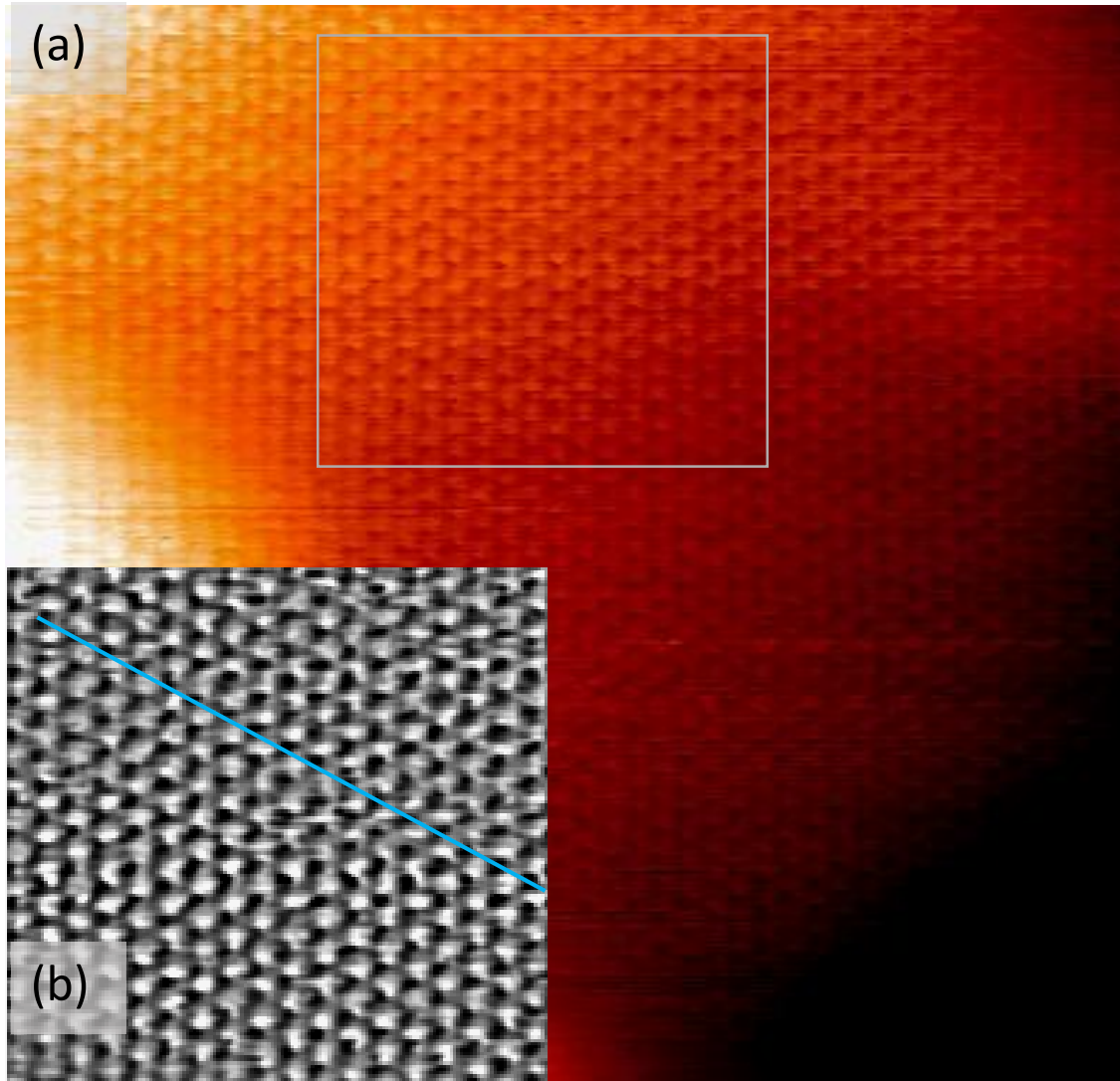
# Graphene on $\beta$ -Si<sub>3</sub>N<sub>4</sub>(0001)/Si(111)

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NEST



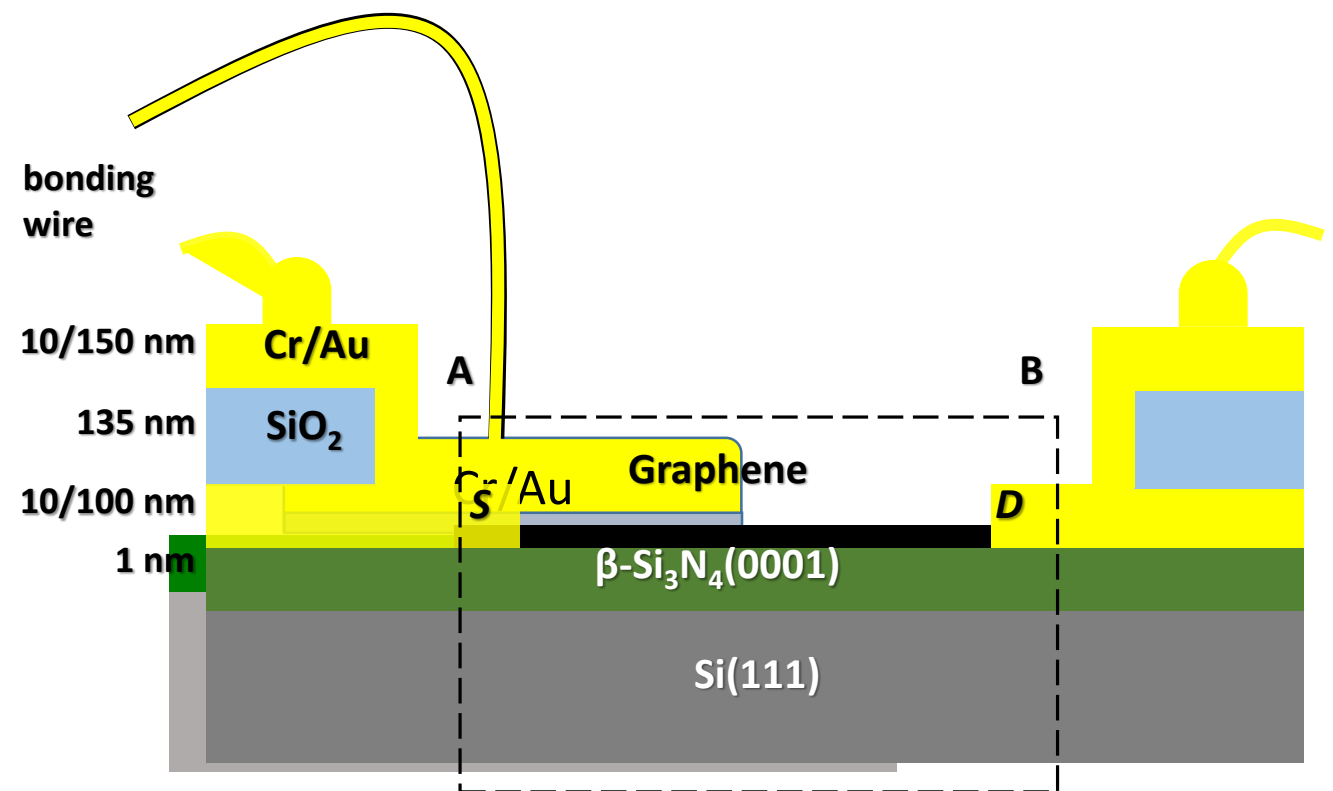
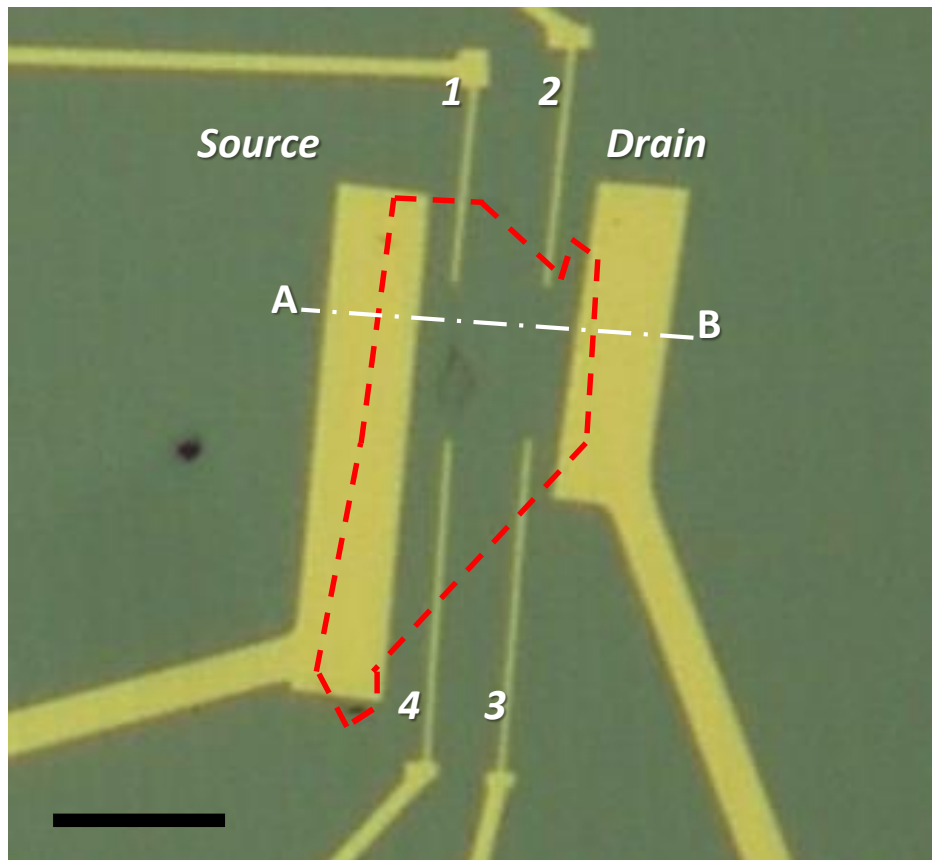
National Enterprise for nanoScience and nanoTechnology



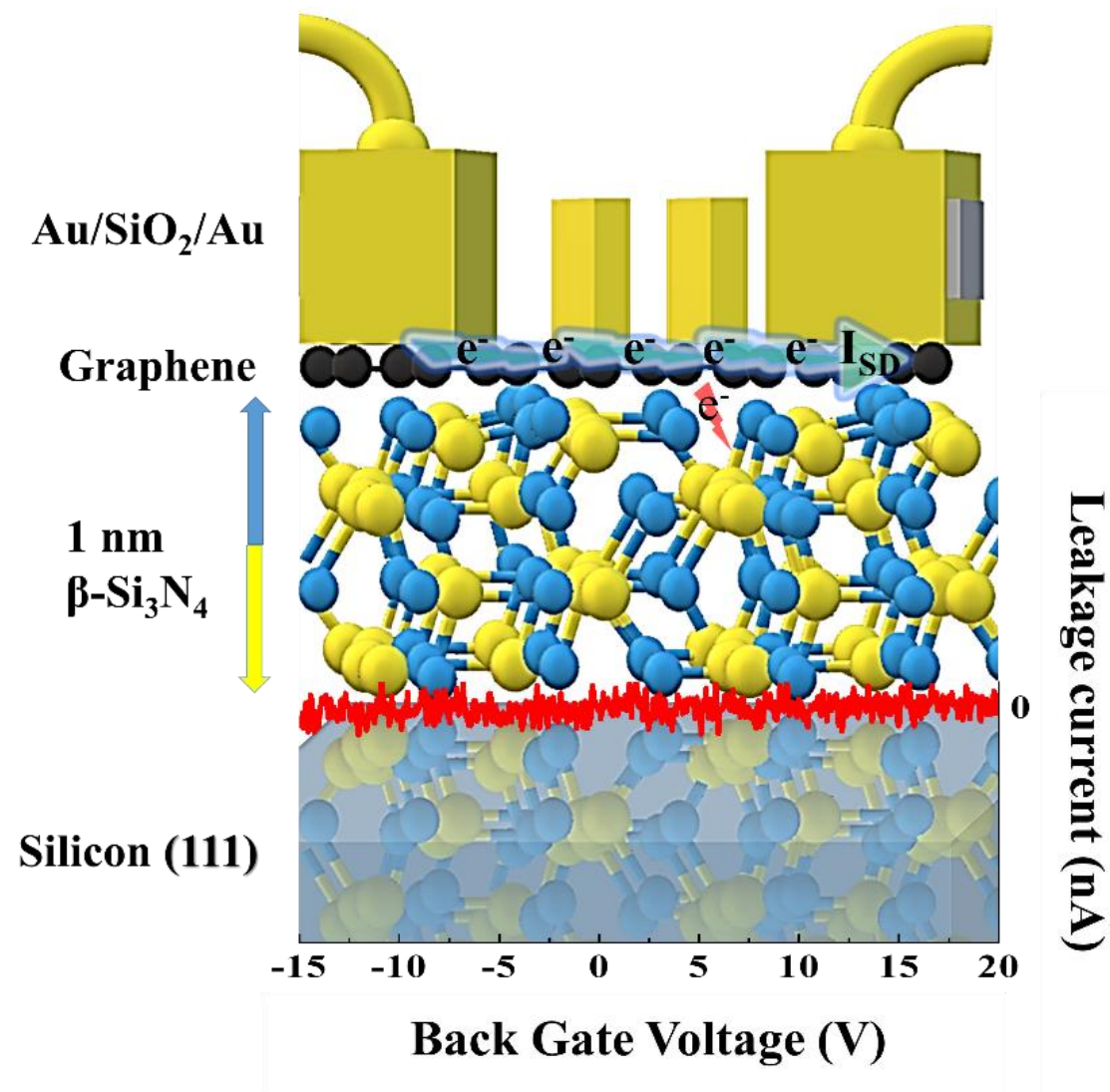
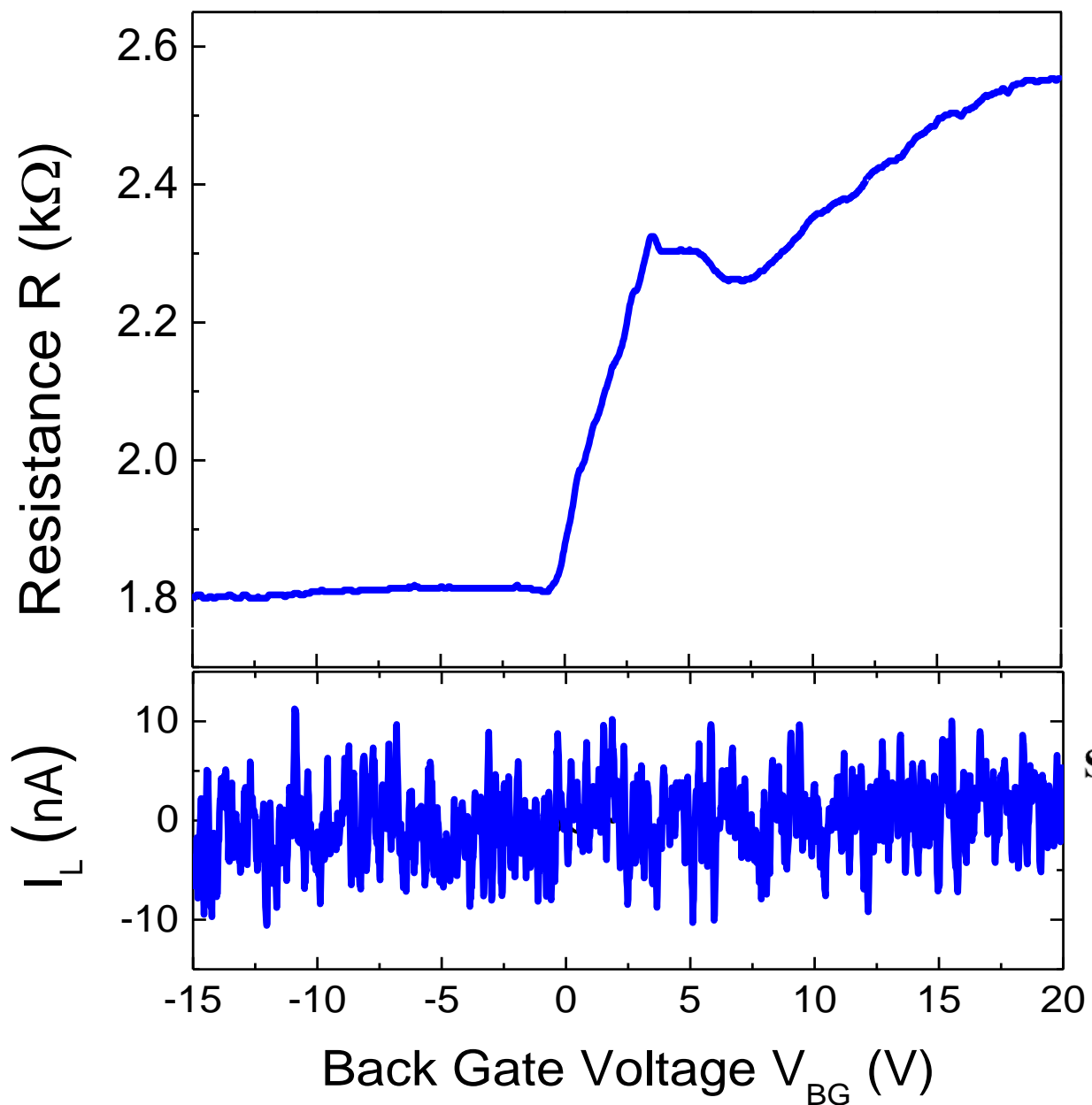
# Magnetotransport measurement

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NEST

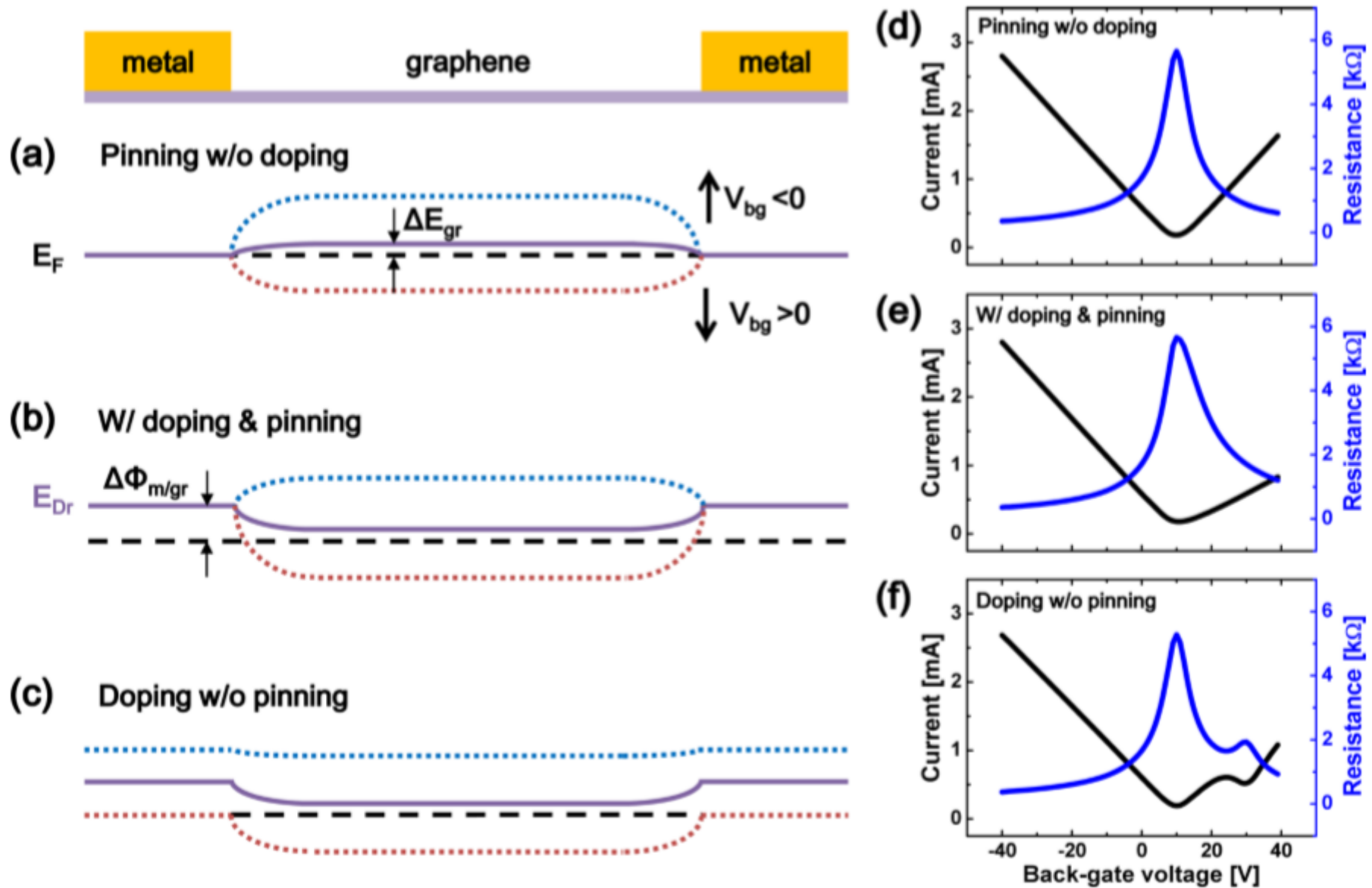


# Electrical transport at 4.2 K



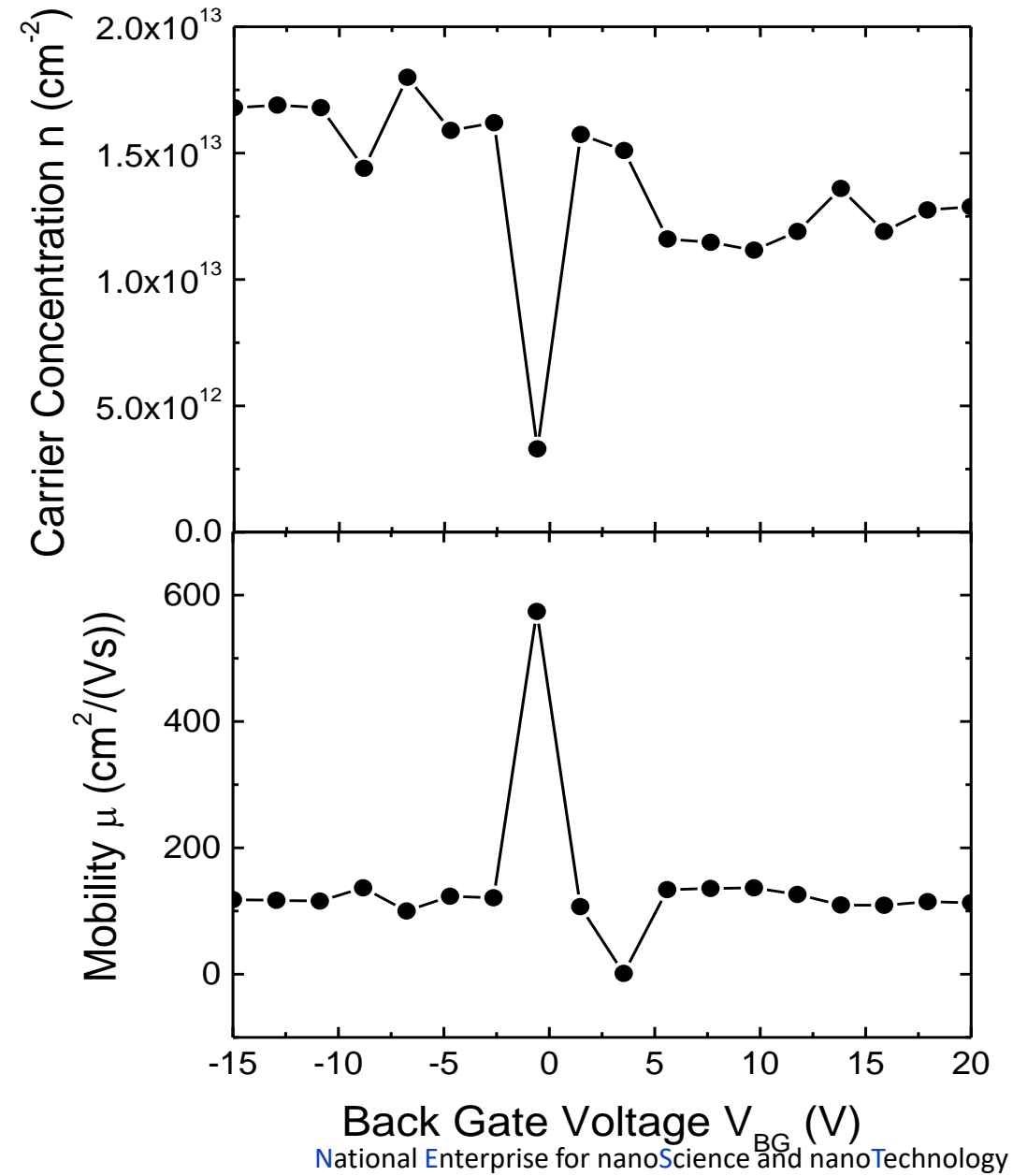
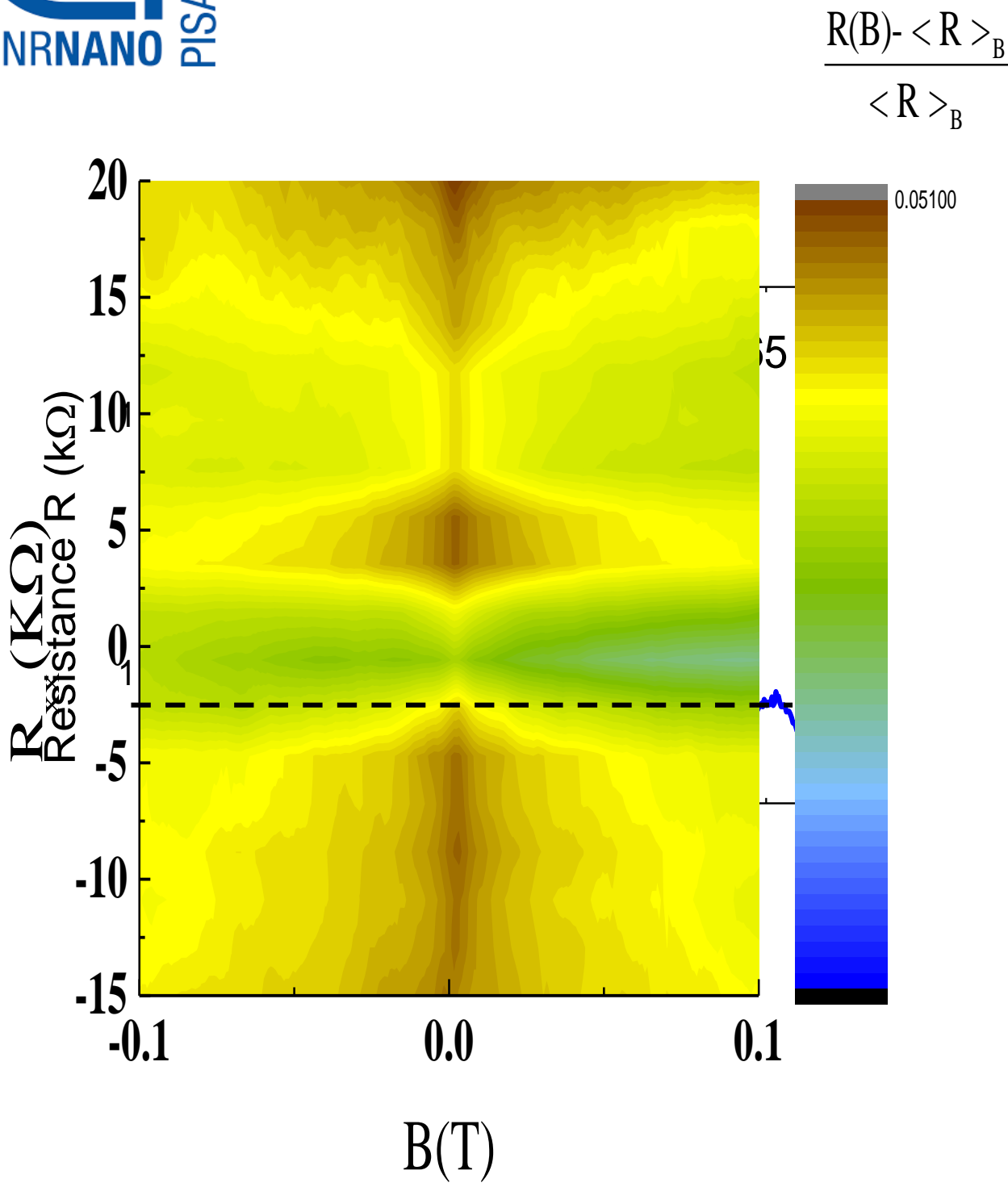
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# The Origin of second Dirac Point...

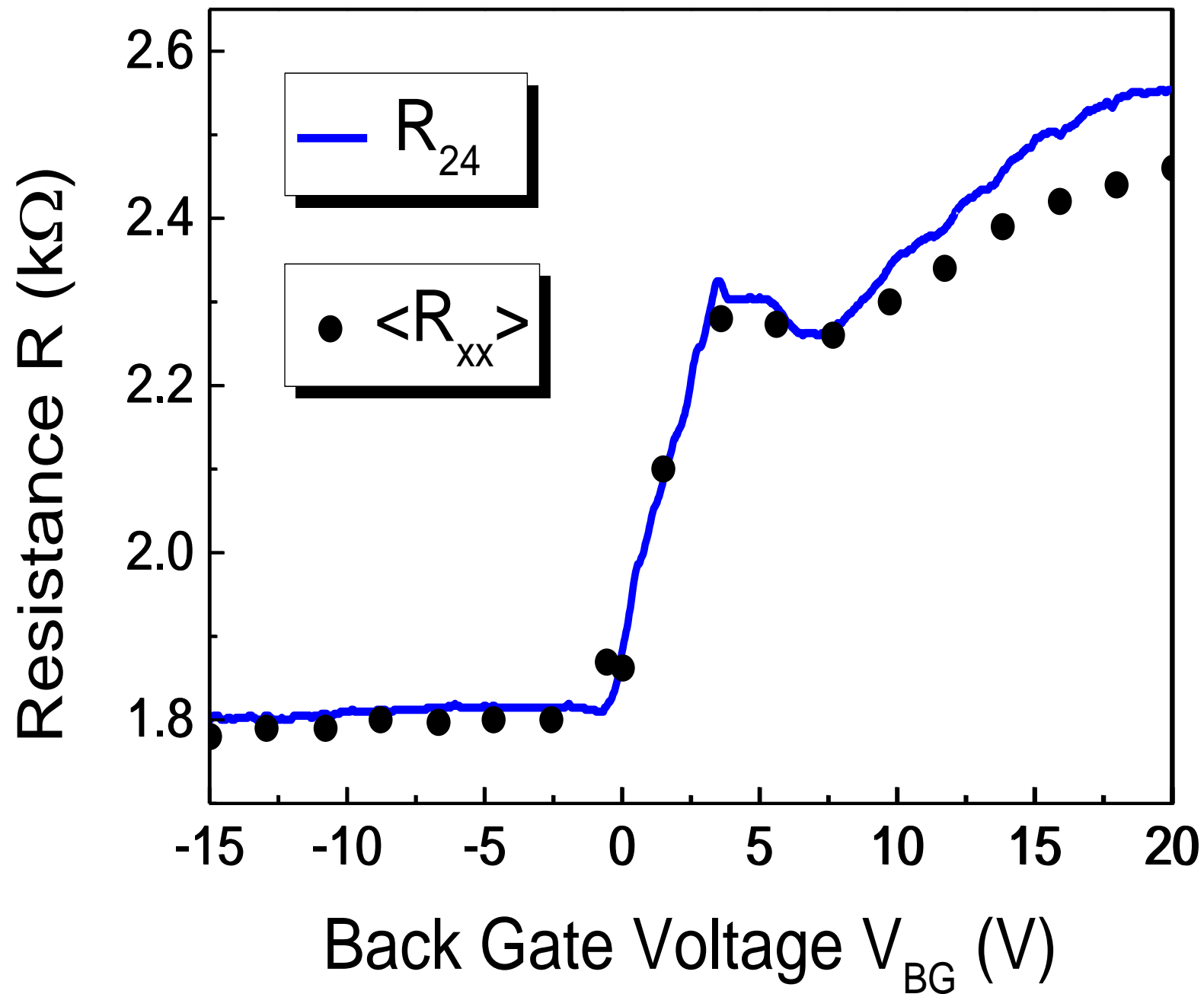


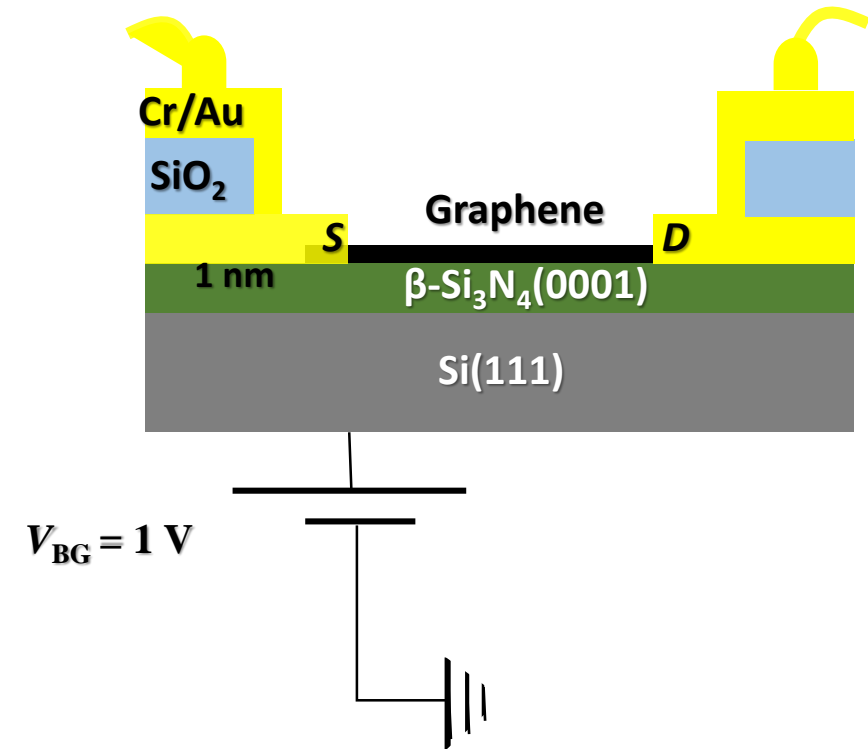
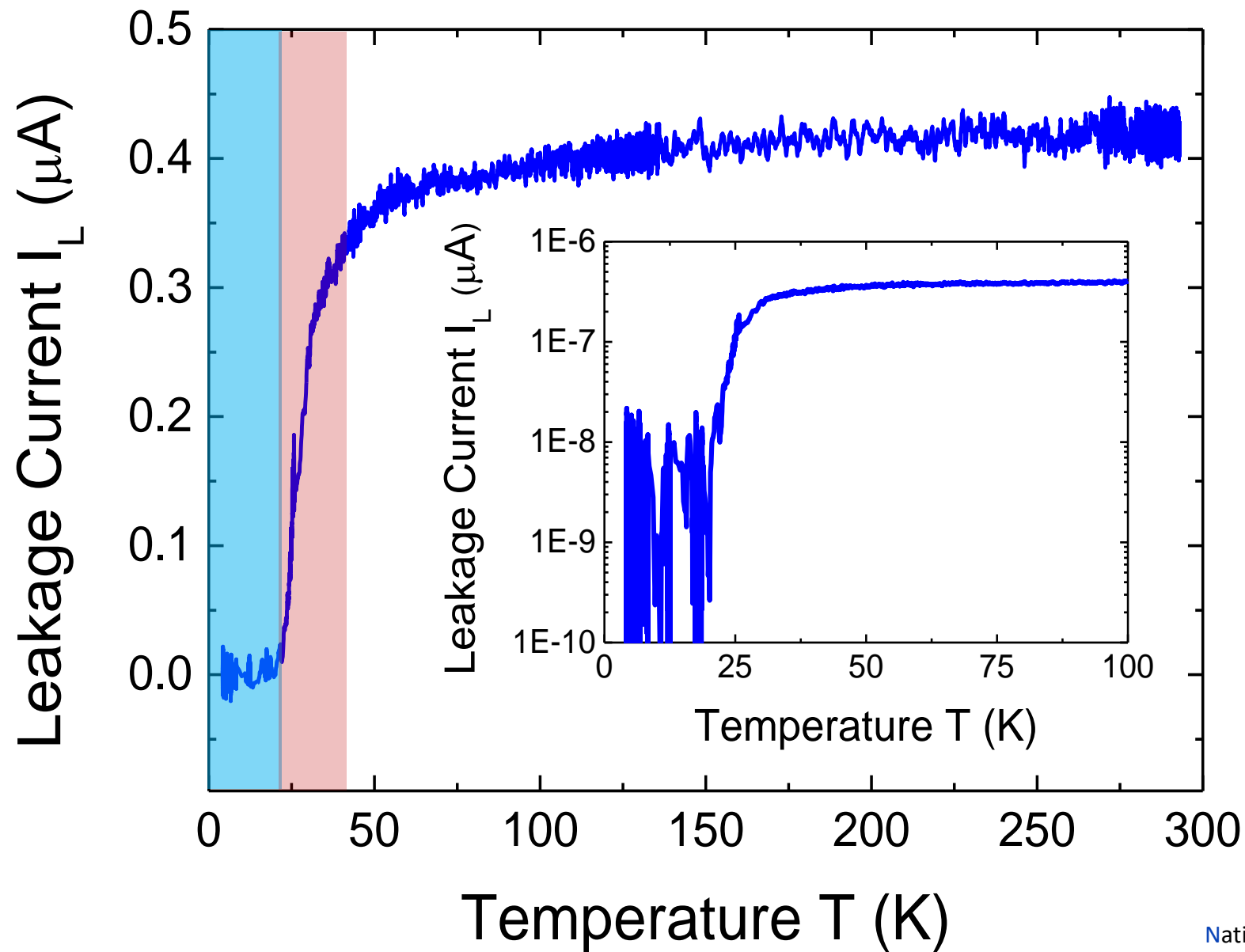
S.M. Song et al. Carbon Let. (2013)

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- ***Large*** area grown ***Crystalline***  $\beta$ -Si<sub>3</sub>N<sub>4</sub>(0001)
- Observation of ***charge carrier modulation***
- ***Very low leakage current at 4.2 K*** in this ultrathin high-k Dielectric

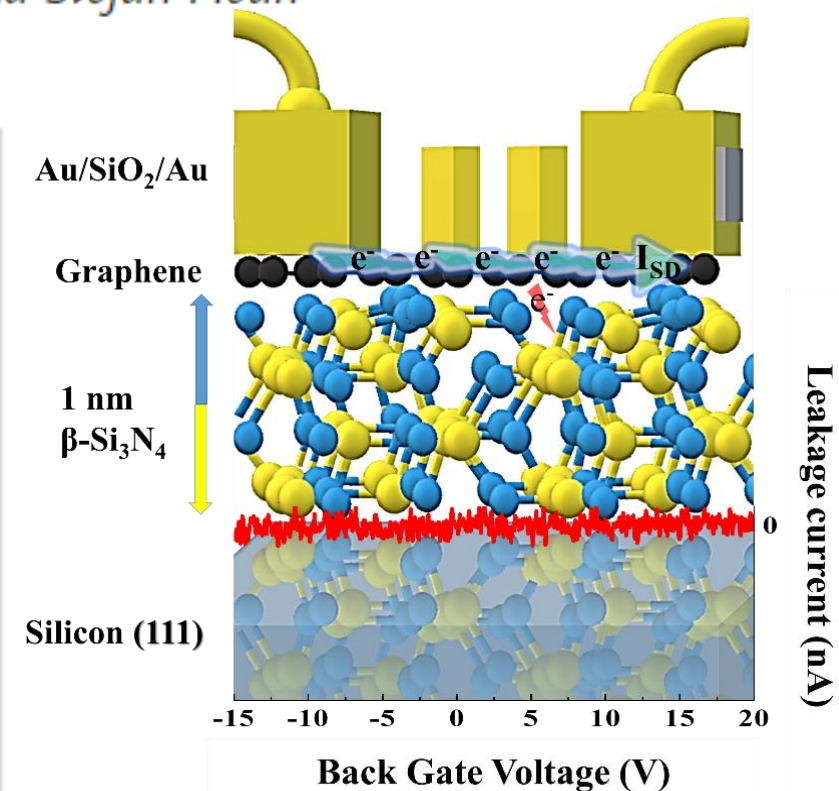
FULL PAPER

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www.advmatinterfaces.de

## Morphology and Magneto-Transport in Exfoliated Graphene on Ultrathin Crystalline $\beta$ -Si<sub>3</sub>N<sub>4</sub>(0001)/Si(111)

Sedighe Salimian, Shaohua Xiang, Stefano Colonna, Fabio Ronci, Marco Fosca, Francesco Rossella, Fabio Beltram, Roberto Flammini,\* and Stefan Heun\*

This work reports the first experimental study of graphene transferred on  $\beta$ -Si<sub>3</sub>N<sub>4</sub>(0001)/Si(111). A comprehensive quantitative understanding of the physics of ultrathin Si<sub>3</sub>N<sub>4</sub> as a gate dielectric for graphene-based devices is provided. The Si<sub>3</sub>N<sub>4</sub> film is grown on Si(111) under ultra-high vacuum (UHV) conditions and investigated by scanning tunneling microscopy (STM). Subsequently, a graphene flake is deposited on top of it by a polymer-based transfer technique, and a Hall bar device is fabricated from the graphene flake. STM is employed again to study the graphene flake under UHV conditions after device fabrication and shows that the surface quality is preserved. Electrical transport measurements, carried out at low temperature in magnetic field, reveal back gate modulation of carrier density in the graphene channel and show the occurrence of weak localization. Under these experimental conditions, no leakage current between back gate and graphene channel is detected.



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*Stefan Heun*



*Stefano Colonna*



*Roberto Flammini*



*Shaohua Xiang*



*Fabio Ronci*



*Lucia Sorba*



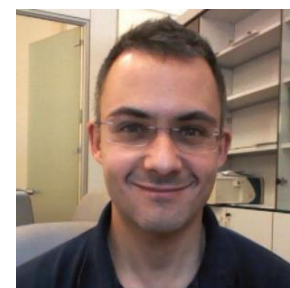
*Omer Arif*



*Francesco Rosella*



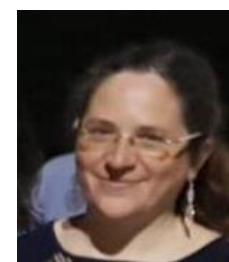
*Daniele Ercolani*



*Valentina Zannier*



*Stefano Rodaro*



*Francesca Rossi*



*Ang Li*



*Thanks for your attention*





این مسجد